



Analysis of SiW-ECAL technological prototype beam test with electron beam



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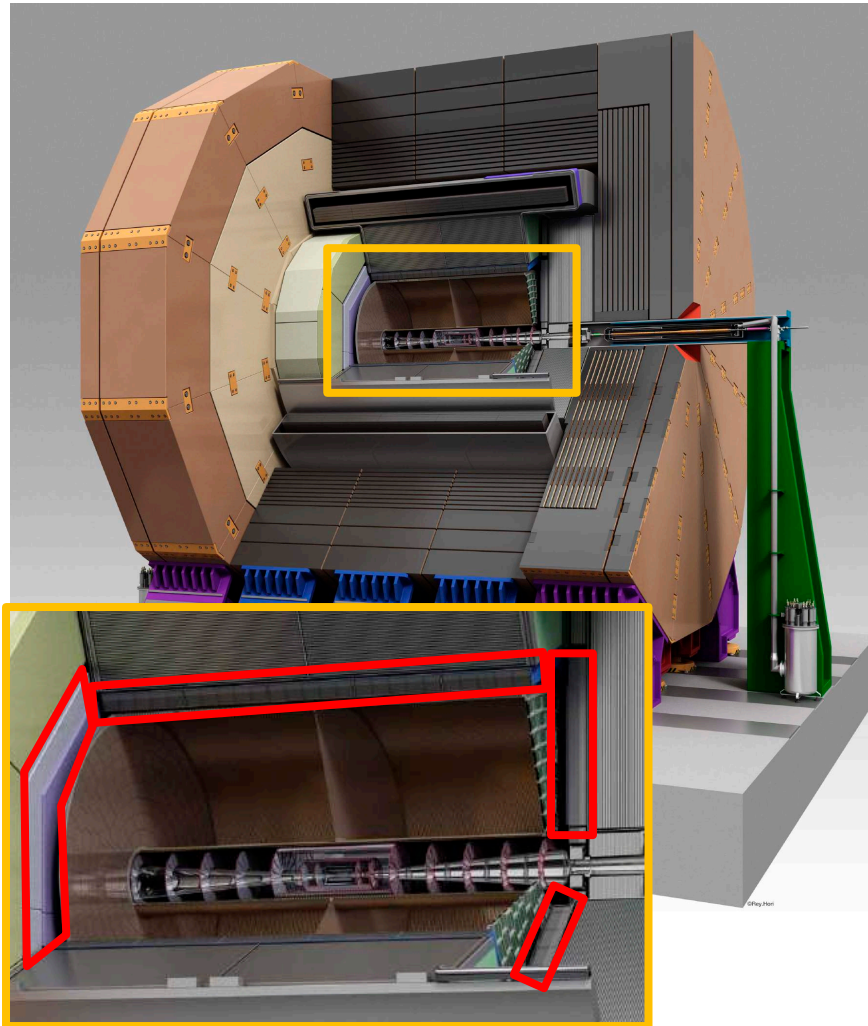


CHEF2019 @ Fukuoka, Japan
29th Nov. 2019

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International Large Detector



One of the detector concepts at the ILC

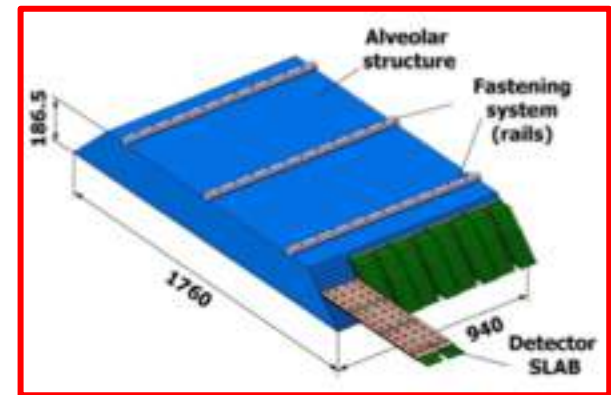
Optimized for Particle Flow Algorithm

- Reconstruct & identify all the particles

Components

- Vertex detector
- Trackers
- Calorimeters
 - ECAL
 - ScW-ECAL
 - SiW-ECAL**
 - HCAL
- Muon Yoke

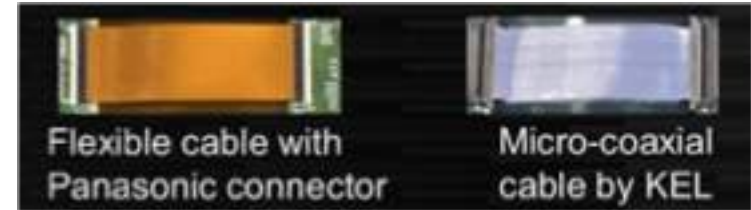
etc.



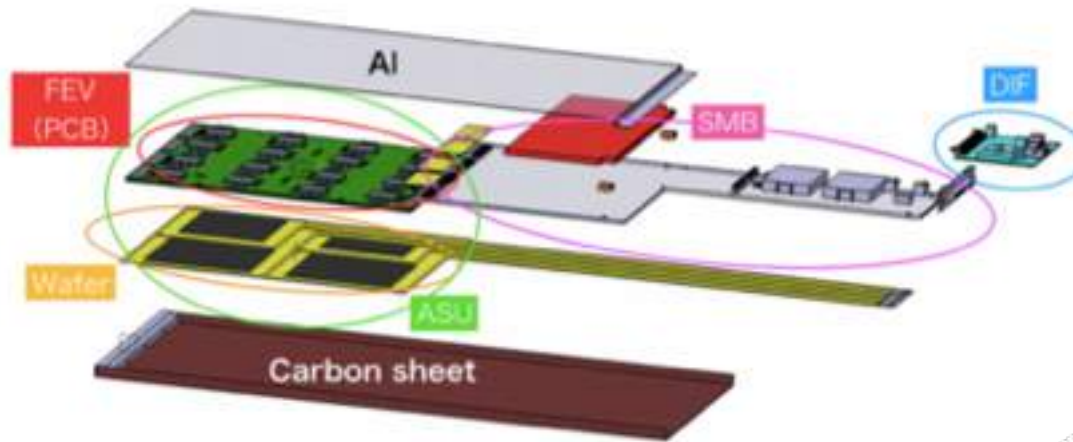
R&D of SiW-ECAL technological prototypes

Major changes in FEV11 → 13 and SMBv4 → v5

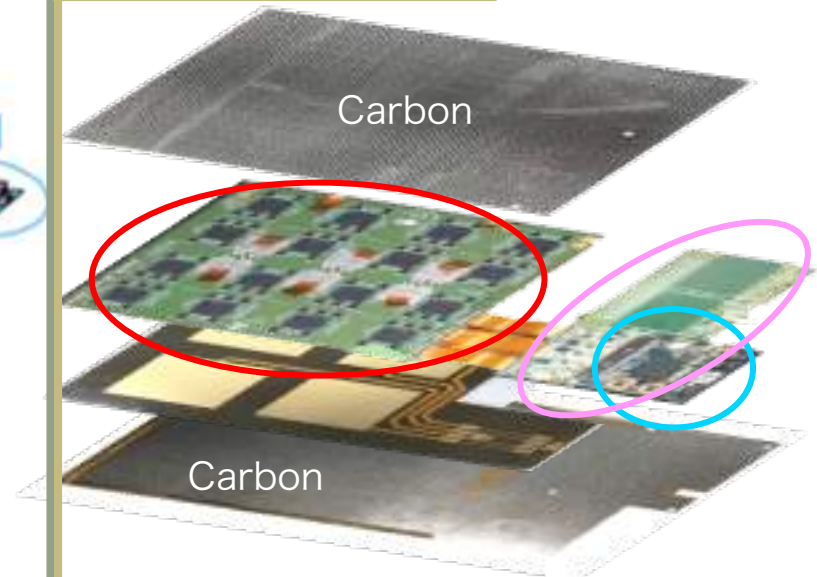
- ASIC: SKIROC2 → 2A
 - Individual threshold control
 - Improvements on TDC
- Smaller SMB footprint
- Connection by 0.4mm-pitch flex cables
 - Two candidates, footprint compatible



FEV11 & SMBv4

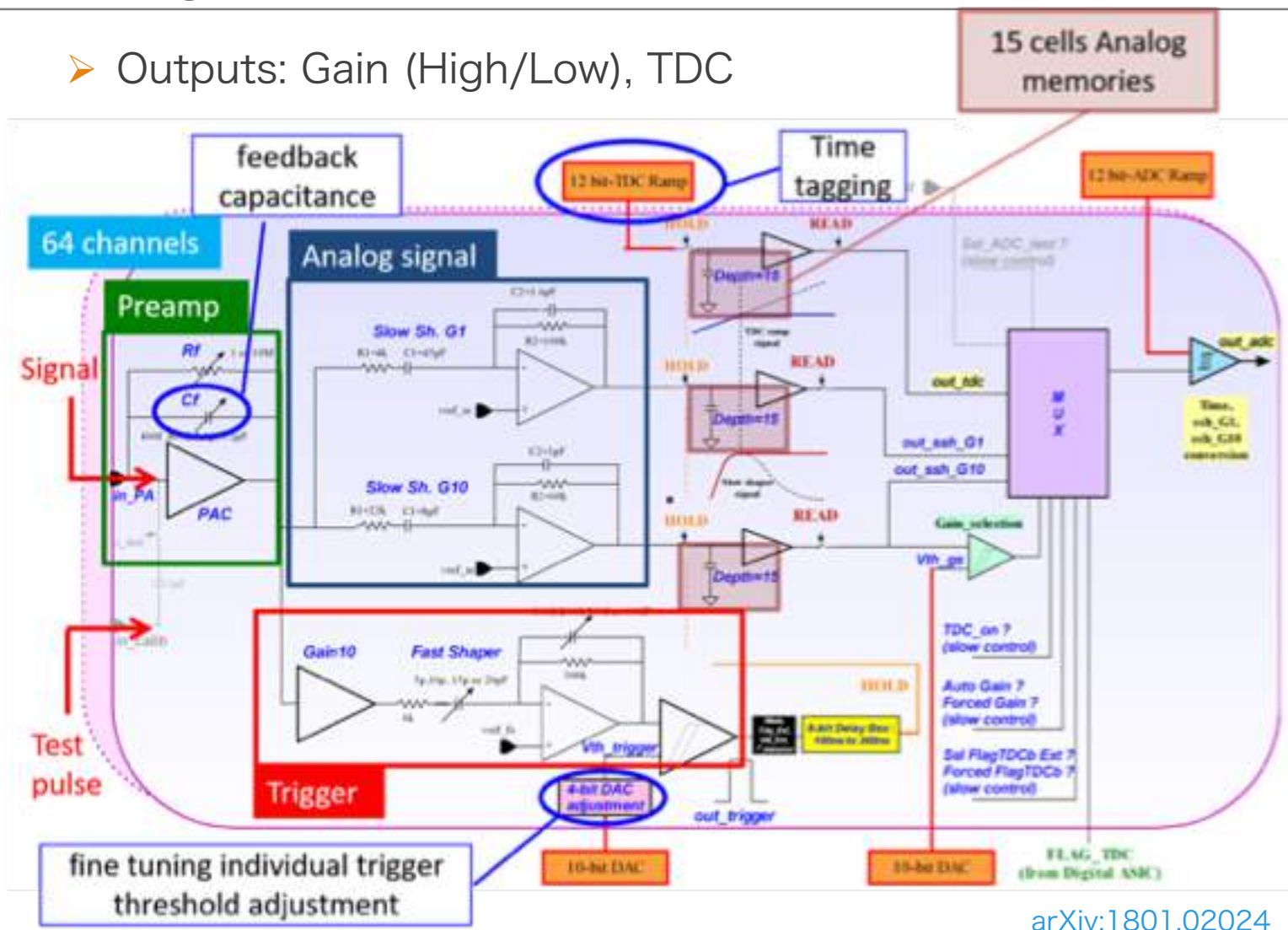


FEV13 & SMBv5



Analogue core: SKIROC2A

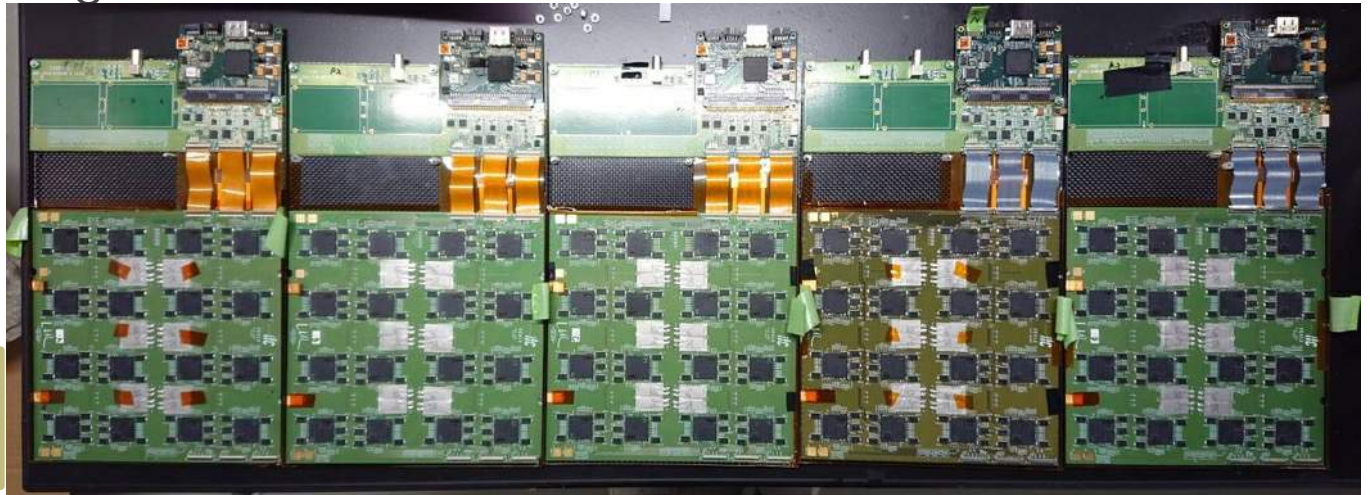
- Outputs: Gain (High/Low), TDC



arXiv:1801.02024

FEV1 3-Jp Status

- ASIC: SKIROC2A
- Si thickness: 320 μ m & 650 μ m **New!**
 - 256 ch/sensor \times 4 sensor/slab
- FEV-SMB Connection: Flexible cable or Micro-coaxial cable
- EM shielding: w/ Carbon frame and cover
- Power Pulsing

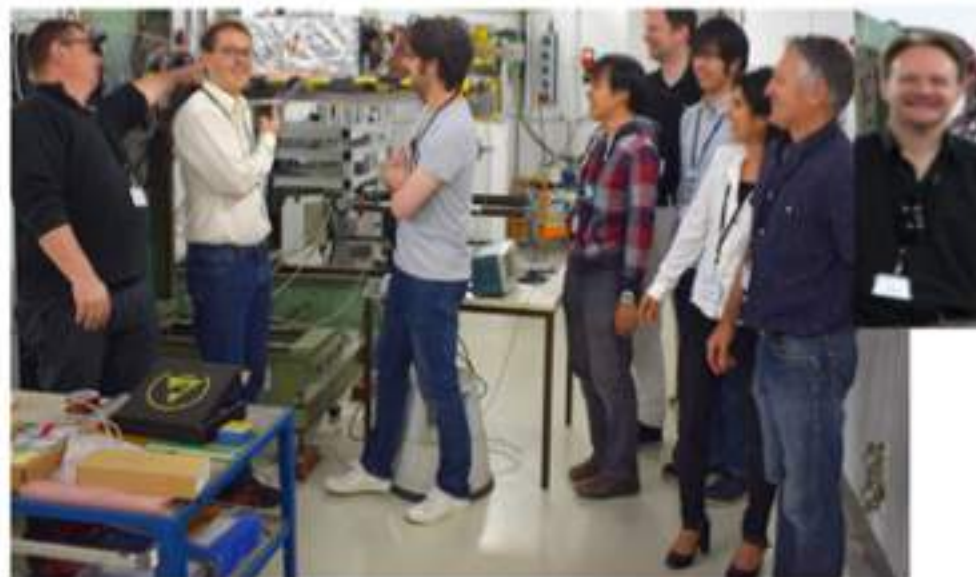


Total 5 slabs
in Kyushu U., Japan

slab ID	P1	P2	P3	K1	K2
Si thickness	650 μ m	650 μ m	320 μ m	650 μ m	650 μ m
Assembly	in Kyushu U.	in Kyushu U.	in Kyushu U.	in LLR	in Kyushu U.

Beam Test 2019 @ DESY

- Beam time:
 - 24th June - 7th July at DESY test beam facility
 - e⁻ beam: 1 - 5 GeV
- Presence from:
- Support & Hardware from:

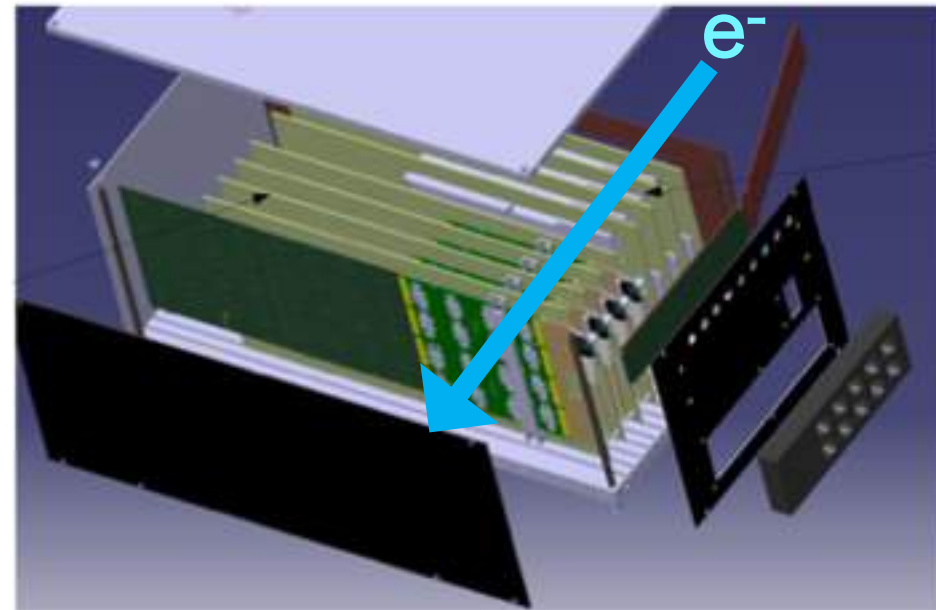
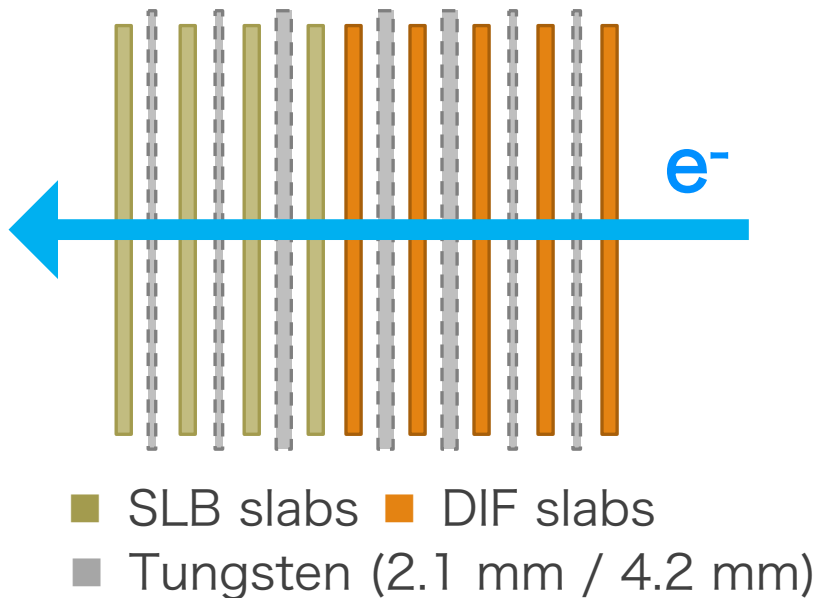


Beam Test 2019 @ DESY

- Beam time:
 - 24th June - 7th July at DESY test beam facility
 - e⁻ beam: 1 - 5 GeV
- Objectives:
 - Comparison of ASU based on BGA and based on Chip-On-Board (COB)
 - Test of new SL-Boards (SLB)
 - **Validation of FEV13-Jp** ← Target of this talk
- Programs:
 - MIP program (w/o Tungsten)
 - **Position scan for MIP calibration**
 - TDC test
 - Angled beam: 25 deg.
 - **Retriggering / double pedestal**
 - Shower program (w/ Tungsten)
 - **Energy measurement**
 - Response from large signal
 - TDC / auto gain
 - Edge effect

Setup for Beam Test

- Devices: 2 types of readouts
 - DIF based slabs: FEV13-Jp × 5
 - SLB based slabs:
 - COB × 2
 - FEV12 × 2
- Absorber: Tungsten
 - $X_0 = 3.5$ mm, $R_M = 9$ mm, $\lambda_0 = 96$ mm



Procedure for Energy Measurement

Single Slab Analysis

1. Trigger adjustment & Masking of noisy channels
2. Pedestal calibration
16 chips × 64 channels × 15 memories
3. Gain calibration using MIP
16 chips × 64 channels

Multi Slab Analysis [in progress]

1. Timing coincidence
using bunch crossing ID (BCID): $\Delta t = 0.2 \mu\text{s}$
2. Event Building

Trigger Adjustment

- Threshold scan is performed for estimation of S/N_{Trig} and trigger adjustment.

$$S/N_{Trig} \equiv \frac{\mu_{2MIP} - \mu_{1MIP}}{\sigma_{1MIP}}$$

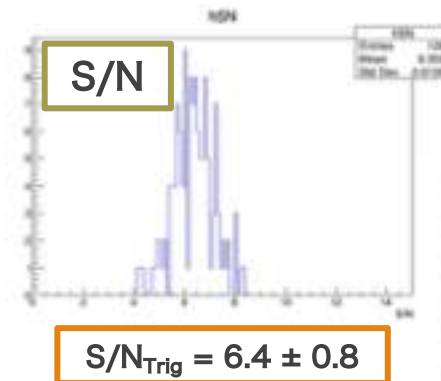
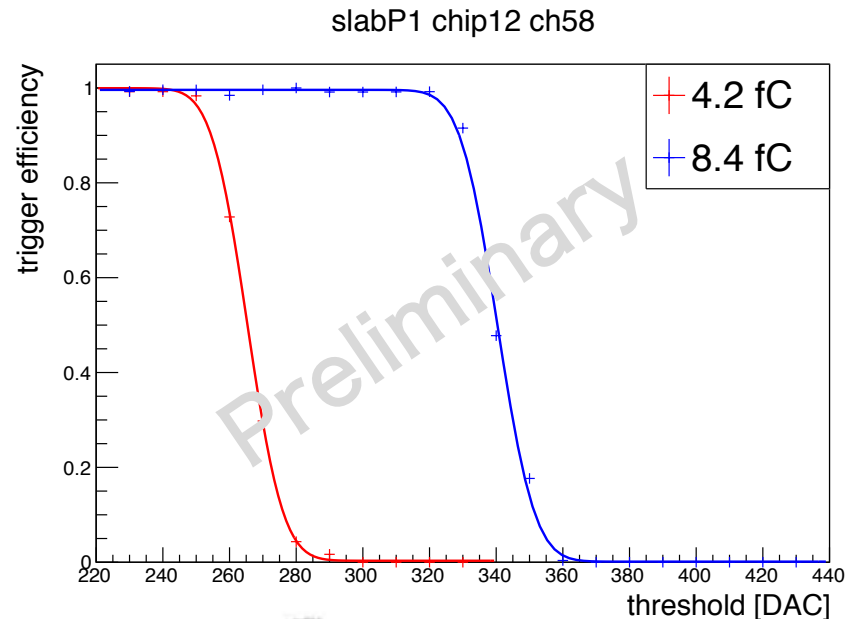
- Test pulse of {4.2, 8.4} fC is injected.
 - 4.2 fC: 1 MIP for 320 μm
- S-curve is fitted by Err-function.

$$f(x) = A \times \text{Erfc}\left(\frac{x - \mu}{\sqrt{2}\sigma}\right) + \text{const.}$$

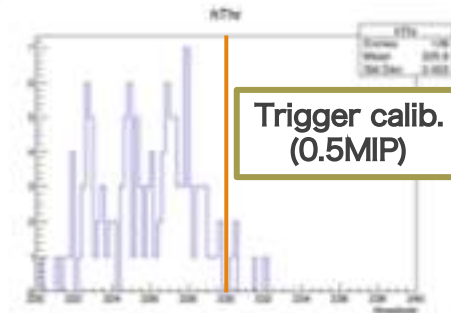
Injection [fC]	4.2	8.4
mean [DAC]	265.4	340.4
sigma [DAC]	12.0	12.5
S/N_{Trig}	6.4 ± 0.8	

- Trigger is set as 0.5 MIP of 320 μm slab: ~ 230 DAC.

S/N_{Trig} is worse (previous: 11.6), under investigation.



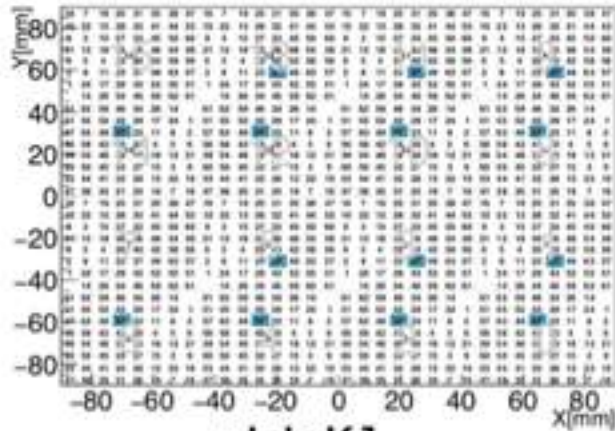
P1, all chips, ch 58-63



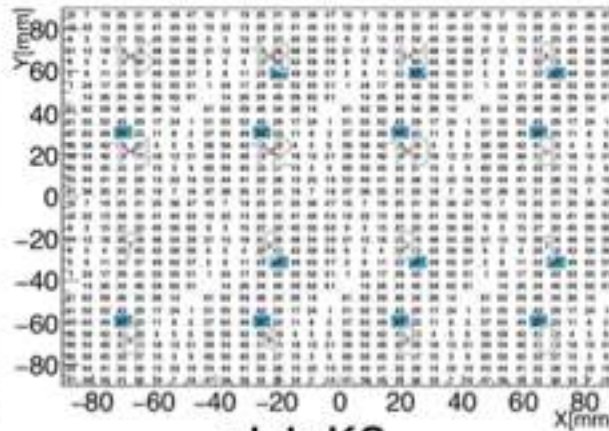
Masking of Noisy channels

- A few channels are noisy after trigger adjustment and masked: 1 - 2 %.
- Individual threshold control was not used because it wasn't ready. → Next TB

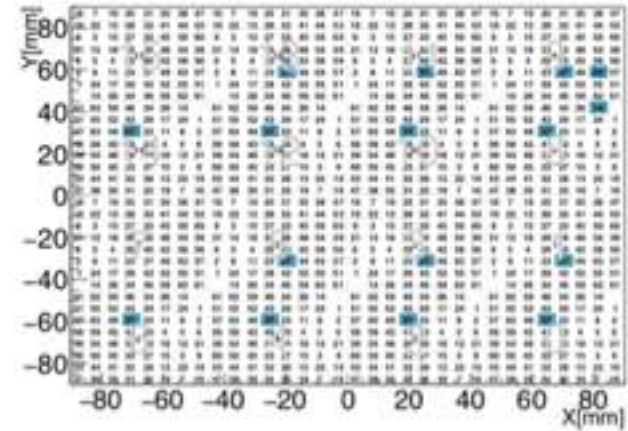
slab P1



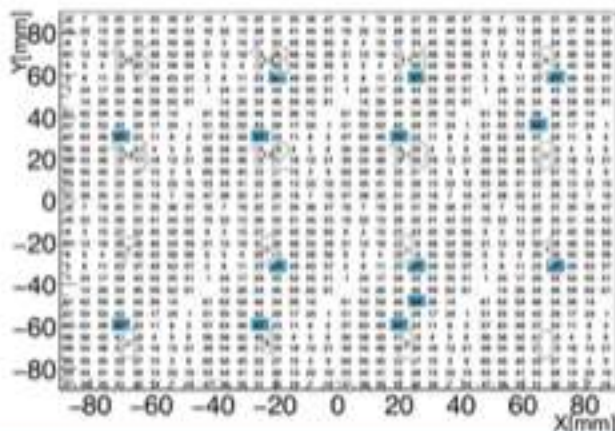
slab P2



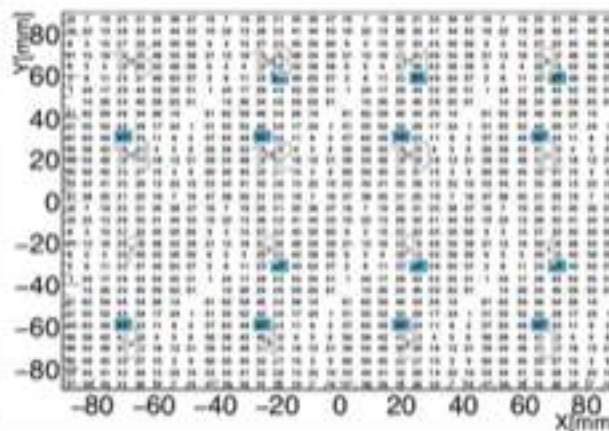
slab P3



slab K1

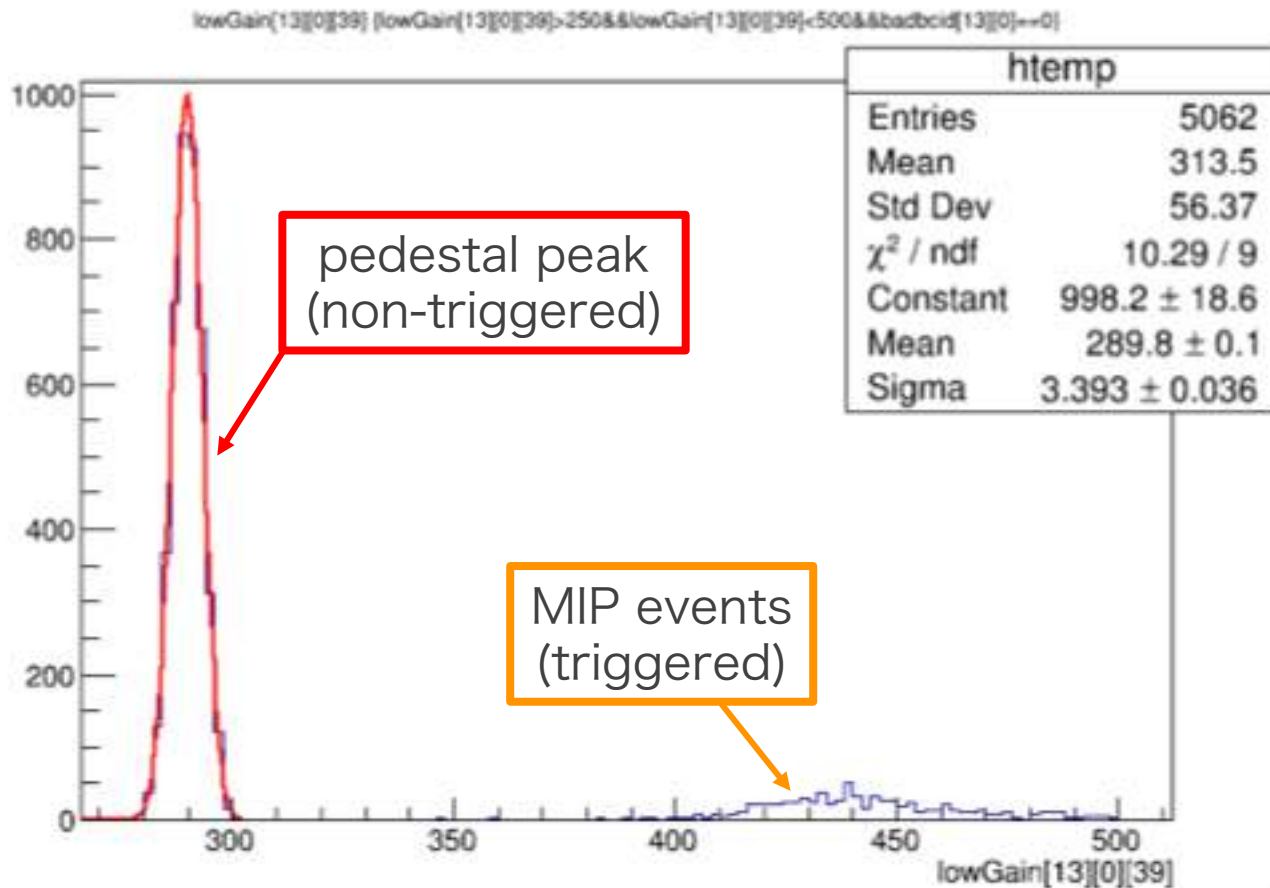


slab K2



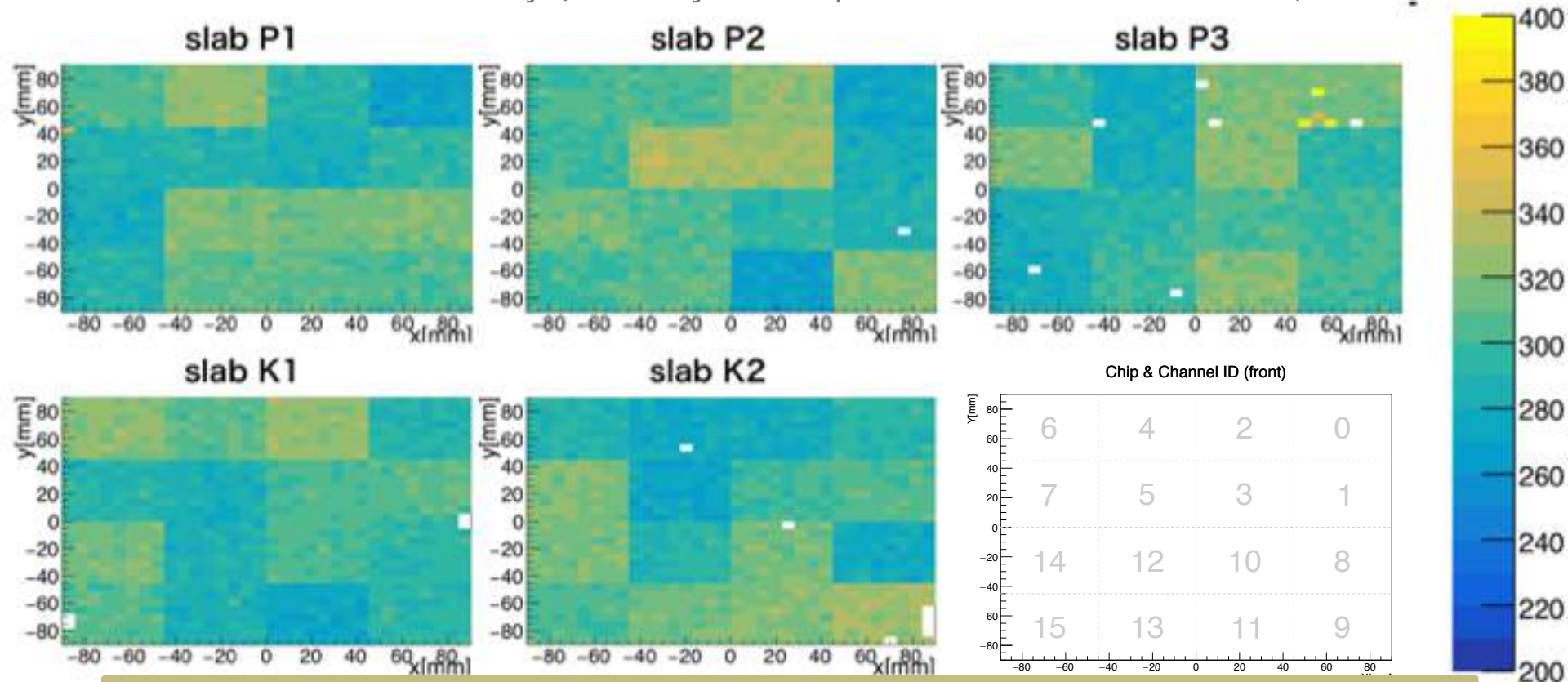
Pedestal Analysis

- Non-triggered ADC output (around ~300 [ADC])
- Fitted by Gaussian



Pedestal Uniformity: Mean

- Mean of Gaussian
- Result of 1st Memory (Memory-cell dependence is referred later.)

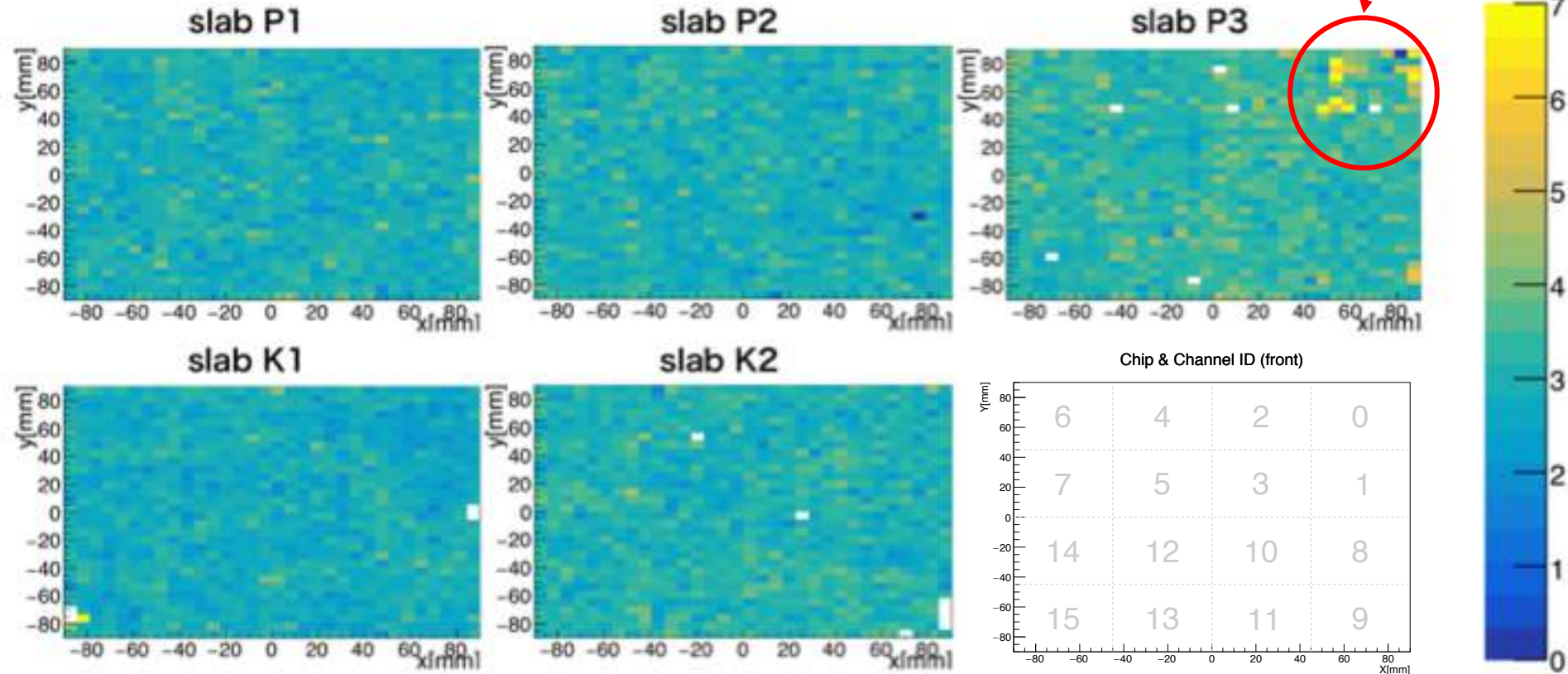


➤ Although there are differences between chips, mean of pedestals looks generally uniform within the same chip.

Pedestal Uniformity: Width

- Sigma of Gaussian
- Result of 1st Memory (Memory-cell dependence is referred later.)

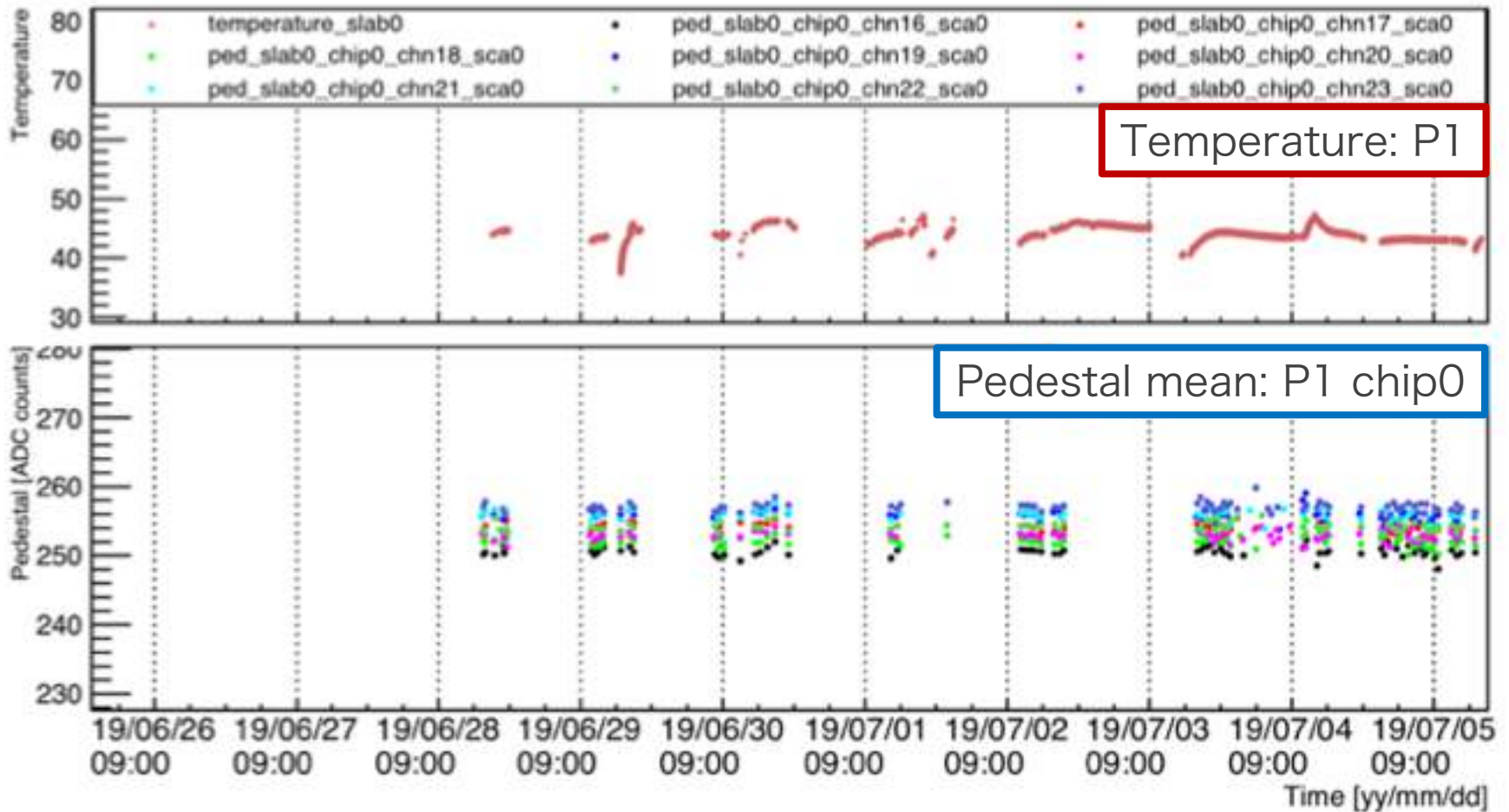
P3-chip0 looks strange.
This chip may be broken.



➤ Width of pedestal is almost uniform (3~4) throughout.

Pedestal Stability

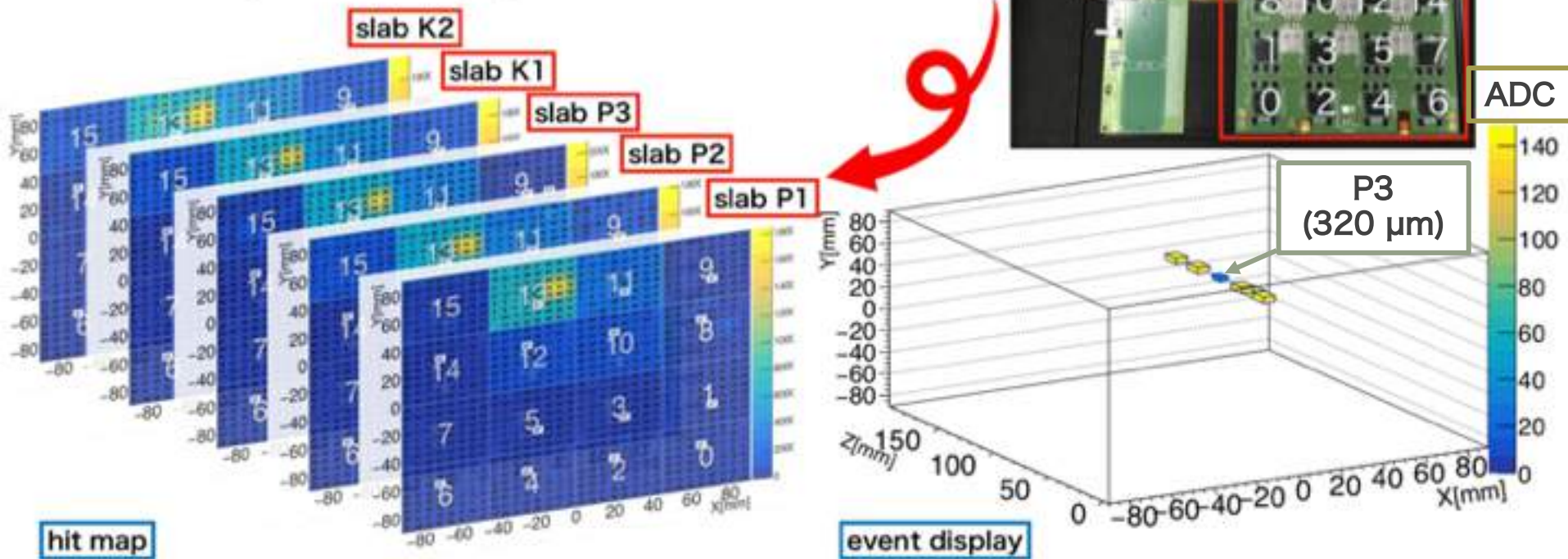
- Pedestal stability is confirmed in this beam time.



MIP event

- MIP program is performed for mainly energy calibration of all the pixels.
- Hit map: Sum of the triggered events
- Event display: ADC output of single event after event building

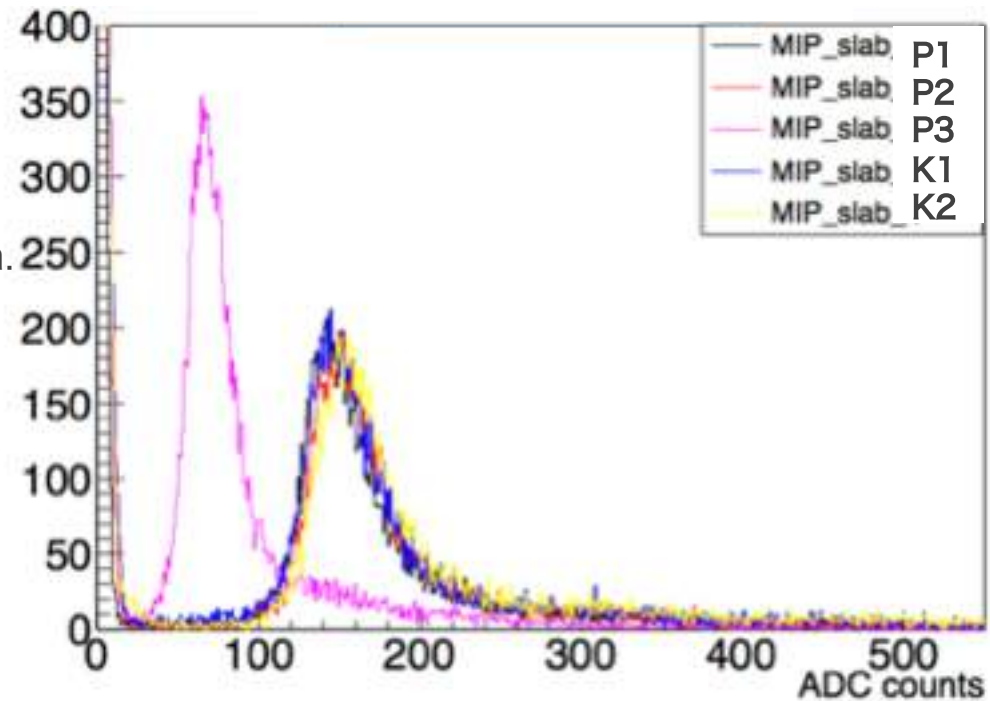
➤ Electron energy: 3 GeV



MIP spectrum

- Typical MIP spectrums of each slabs are shown.
- Pedestal is subtracted.
- Fitted by Lan-Gaus function.
 - Convolution of Landau × Gaussian
- MPV: Most Probable Value
- Definition of S/N_{ADC} :

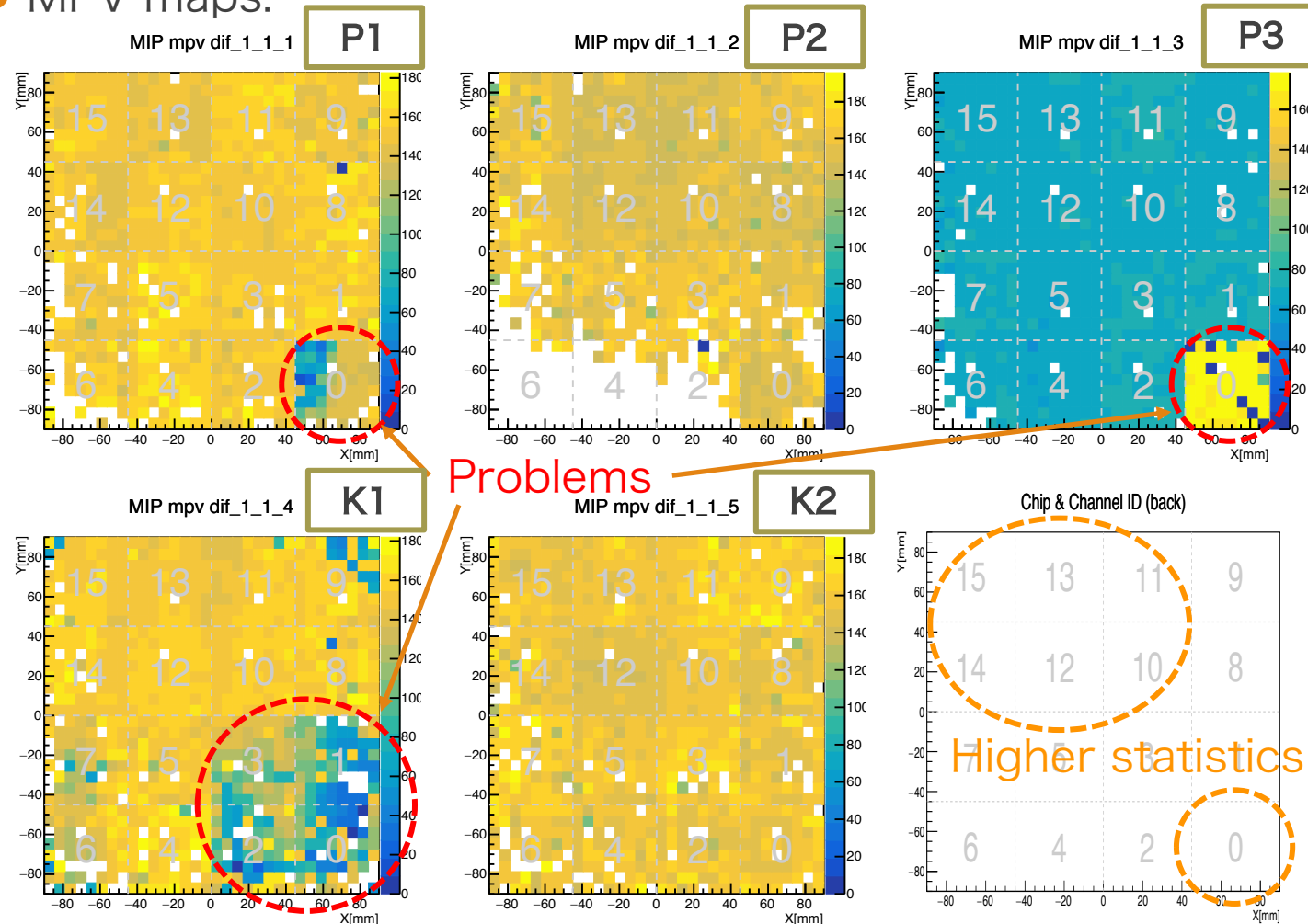
$$S/N_{ADC} \equiv \frac{MPV_{1MIP}}{Width_{pedestal}}$$



slab	P1	P2	P3	K1	K2
thickness	650μm	650μm	320μm	650μm	650μm
MPV	146.5	144.9	71.3	141.4	146.1
Ped_width	3.0	3.0	3.3	2.8	3.1
S/N	49.0	48.9	21.7	50.2	47.5

MIP calibration: Summary

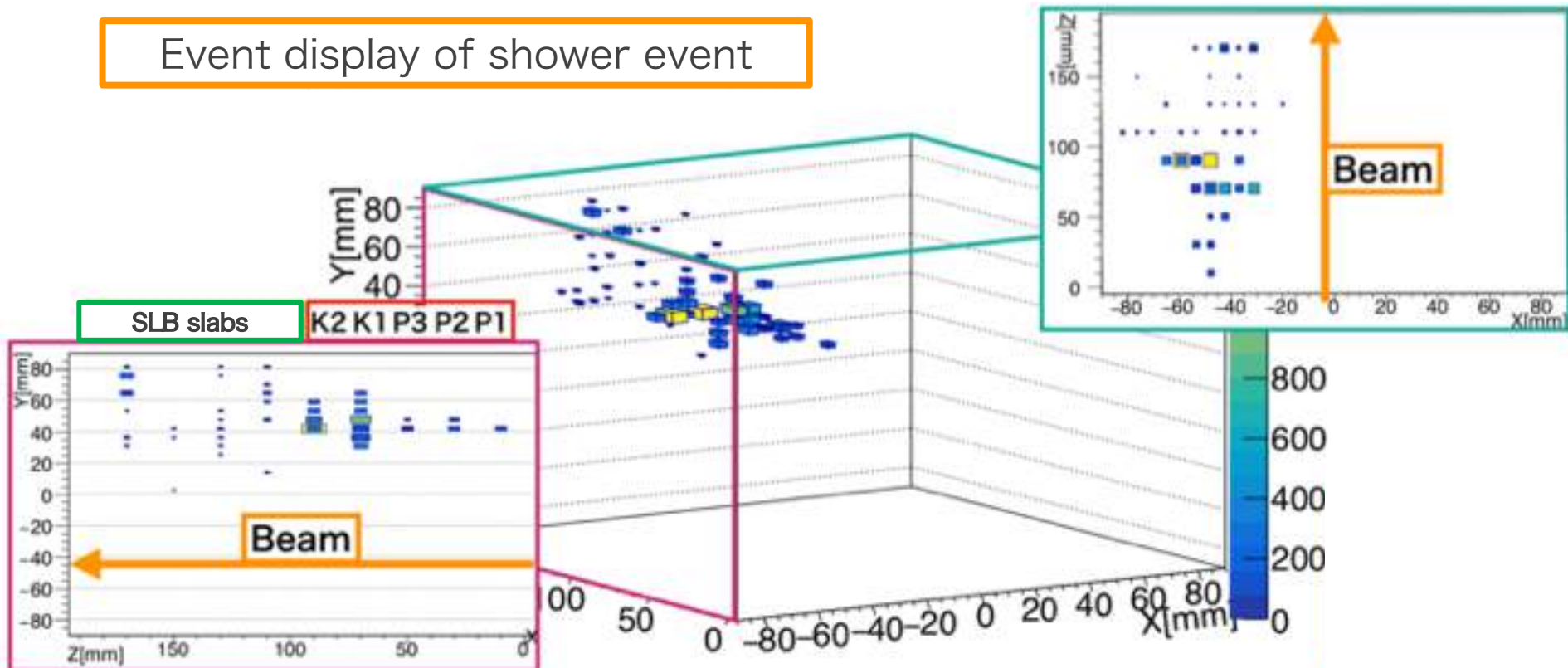
- MPV maps:



Shower event

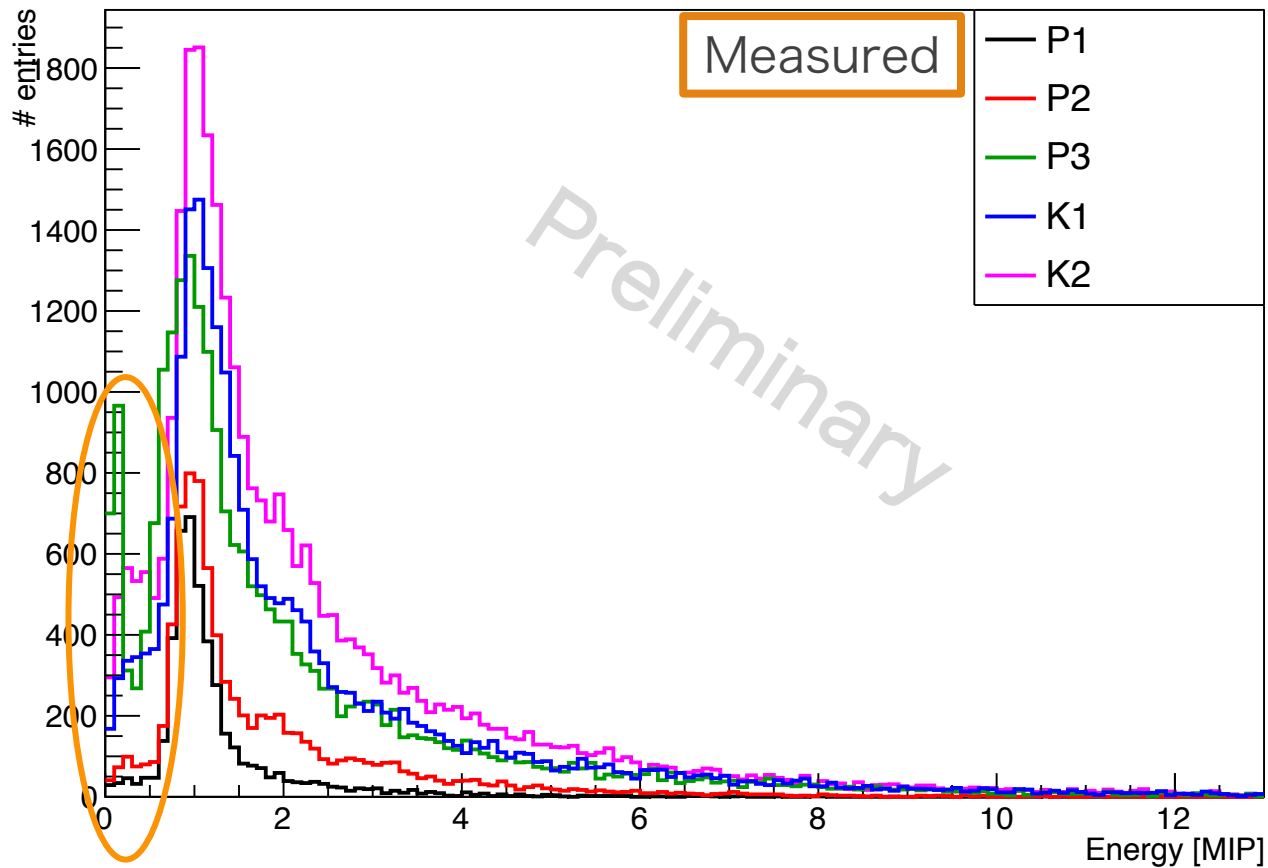
- Using the preceding results, we can finally build events.
 - BCID offsets between SLB-based and DIF-based are corrected.
- A typical event is checked with event display.
 - In this picture, color scale is not converted to energy, still ADC output.

Event display of shower event



Shower Analysis: Hit Energy

- Hit energy after MIP calibration (run 42003)
Single cell hit energy in 3 GeV e^- beam

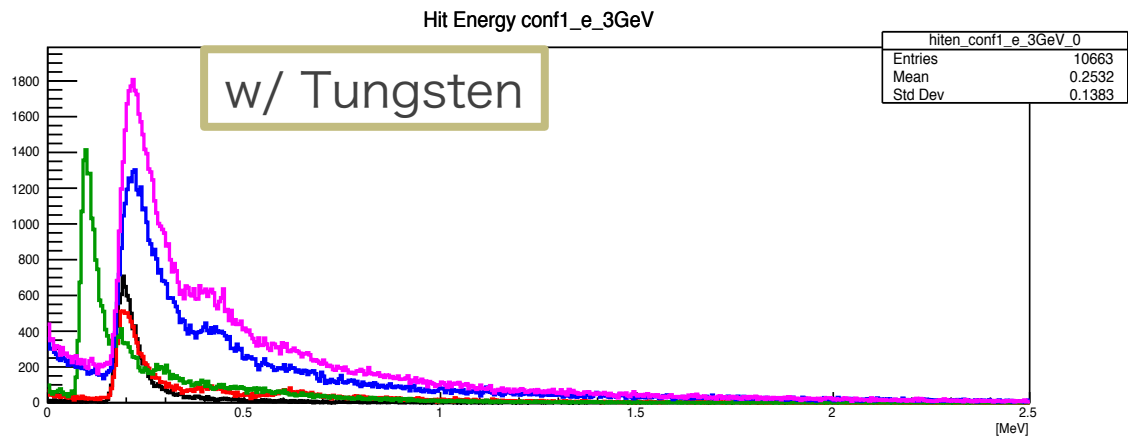
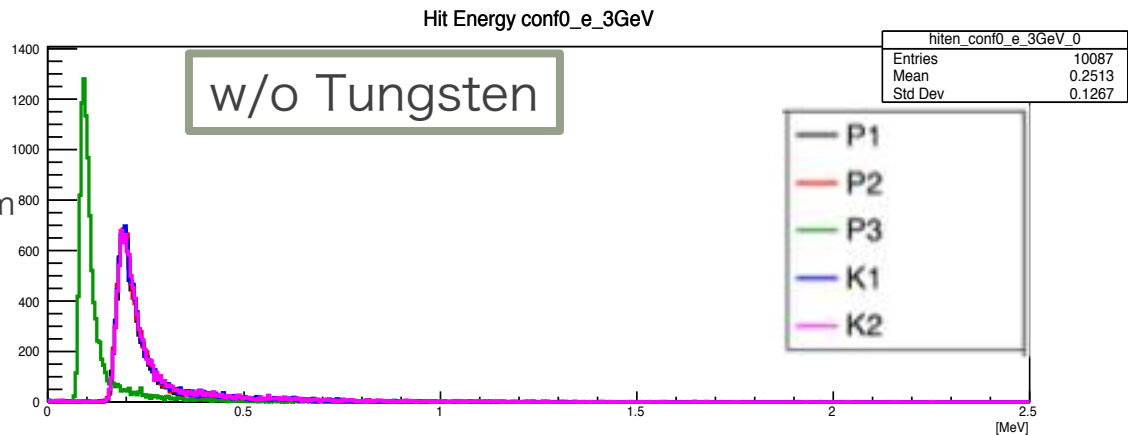


Simulation

- We performed detector simulation for this beam test.
- Simulator: DDSim in iLCSoft

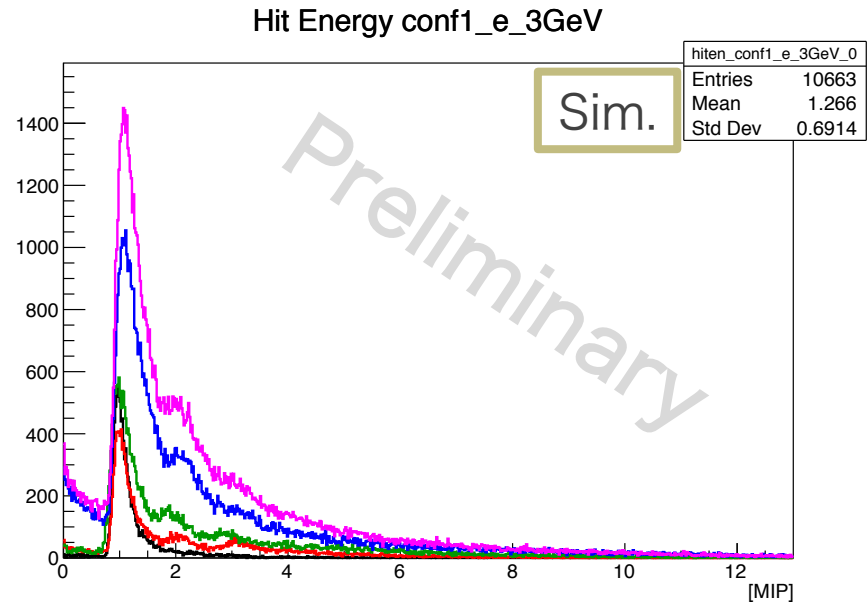
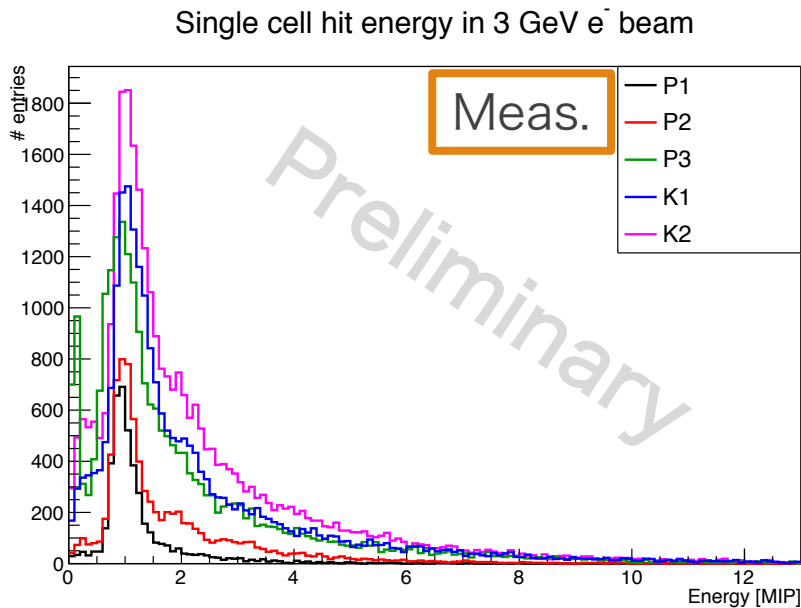
- Structure of FEV13-Jp:

- CF: 0.6mm
- Electronics(Air)
- PCB: K1: 1.6mm, others: 1.8mm
- Glue(Air): 0.08mm
- Si: 0.32mm or 0.65mm
- Glue(Air): 0.08mm
- Kapton(Cu): 0.06mm
- CF: 0.6mm
- Plastic(polyethylene): 5mm



Comparison of Measured and Simulated.

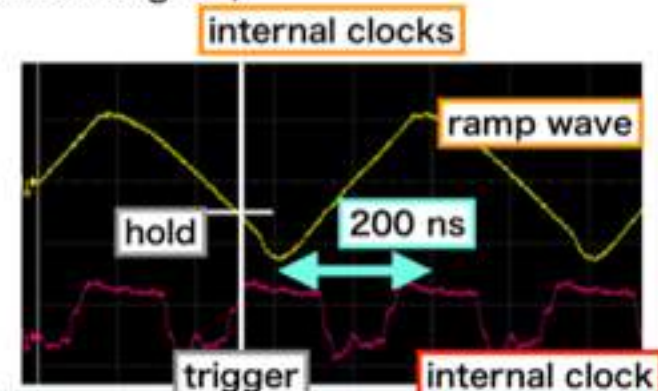
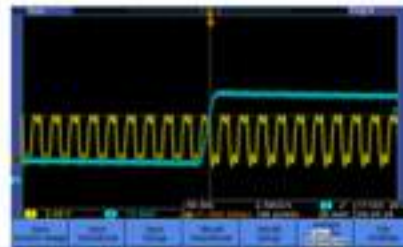
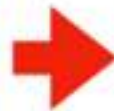
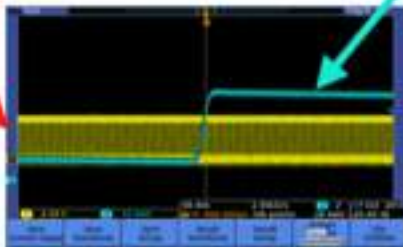
- Simulated results are converted to MIP units and compared to measured ones.
- Work in progress.



TDC Analysis

- TDC mode operation test
- SKIROC2/2A has the ramp wave as one of the internal clocks
 - I measured this ramp waveform for calculating from TDC to real time factor
- The ramp wave can be measured with
 - synchronization of internal and external clock (injection signal)
 - change the phase of injection signal

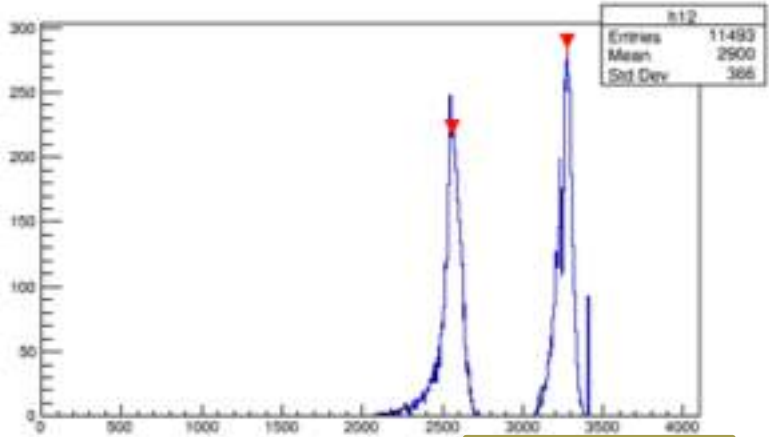
internal clock



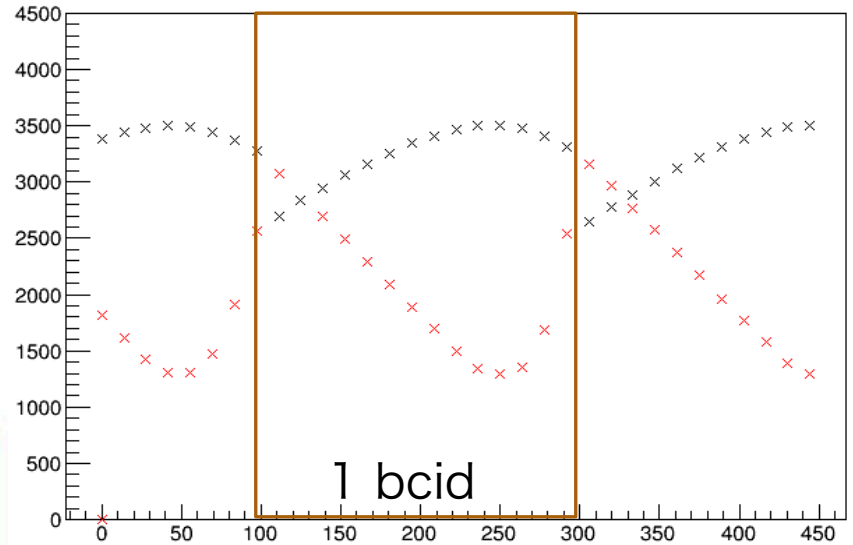
TDC Calibration

- peak search version
 - bcid is not used
- saturation
- phase should be shifted

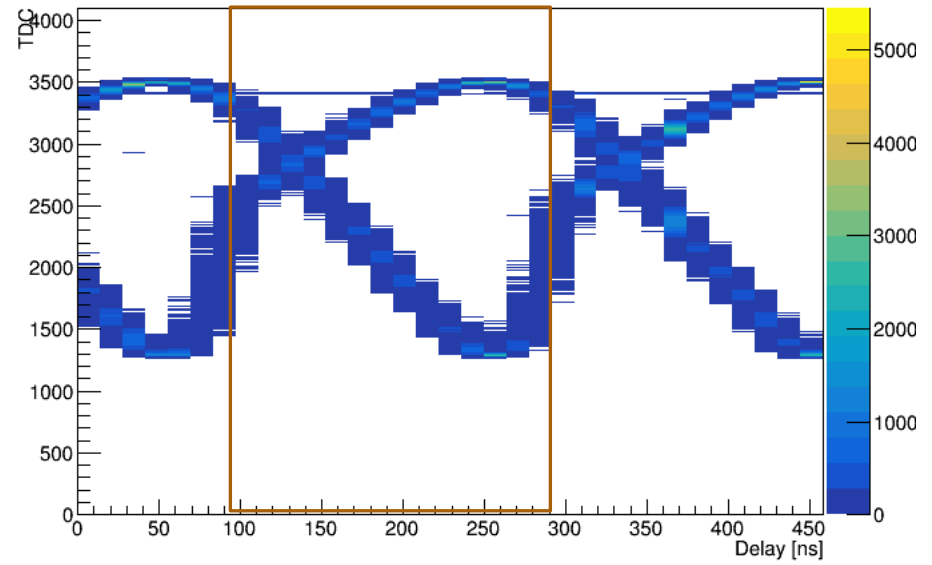
- TDC to real time calibration factors
 - 0.127 ns / TDC count (up)
 - 0.066 ns / TDC count (down)



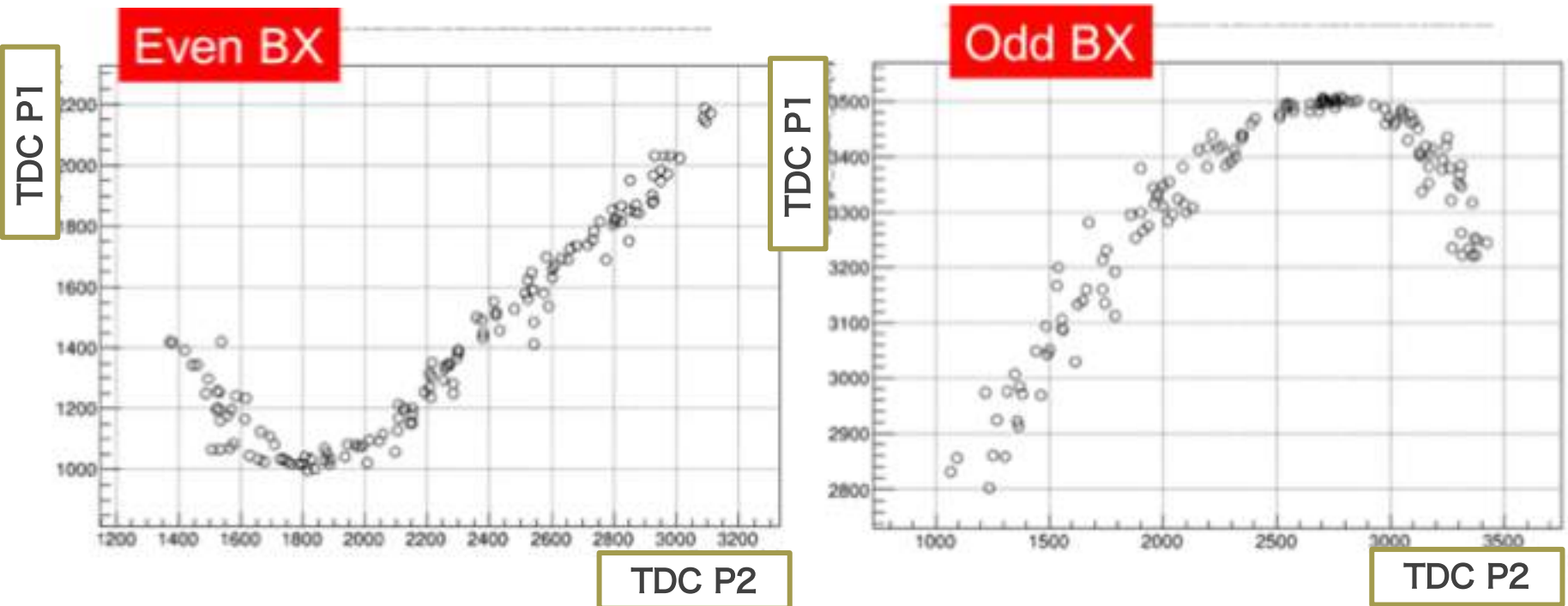
TDC output



test_191021_1_tdc_P1_ch13_3Hz_200kHz, chip12



TDC Correlation with MIP



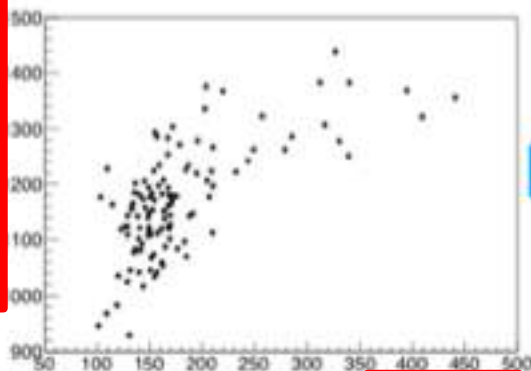
- Correlation of TDC between slab P1 and P2
- Select 1 ch (at the center of the beam), $450 < \text{ADC} < 500$ (to avoid time-walk)
- $\sim 10 / 1$ ns at the normal slope: timing resolution \sim a few ns?
- TDC calibration in progress.

Correction of Time Walk

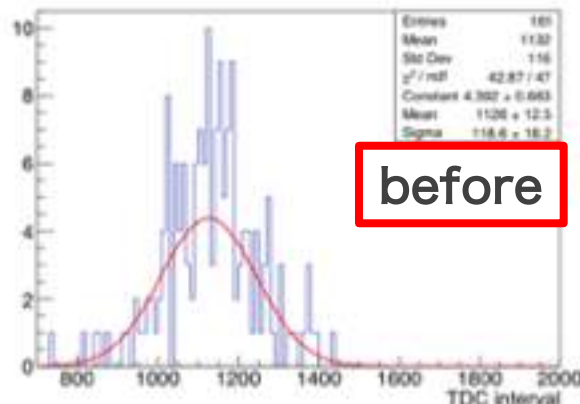
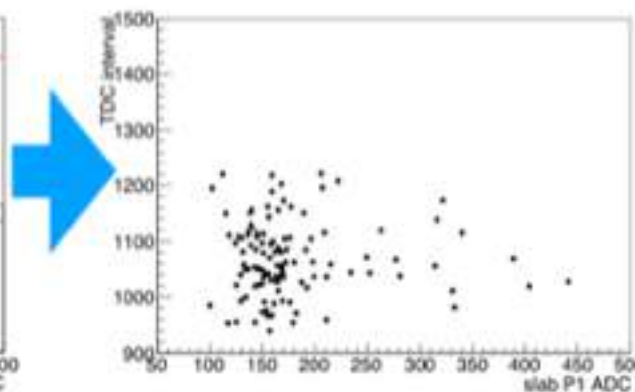
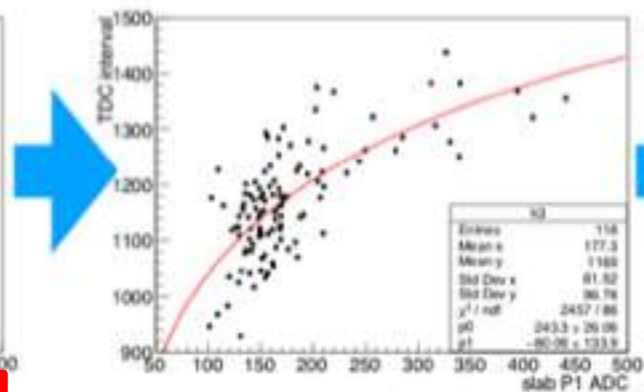
Very Preliminary

- Time Walk: TDC dependence on ADC
- TDC-interval vs ADC are fitted by Log function.
- Width of TDC-interval is improved: 117 → 52.

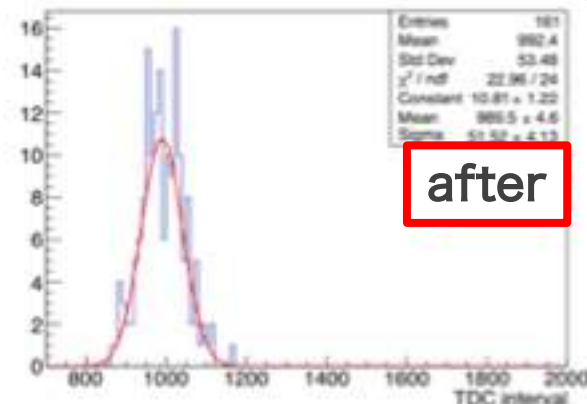
TDC interval



ADC



before



after

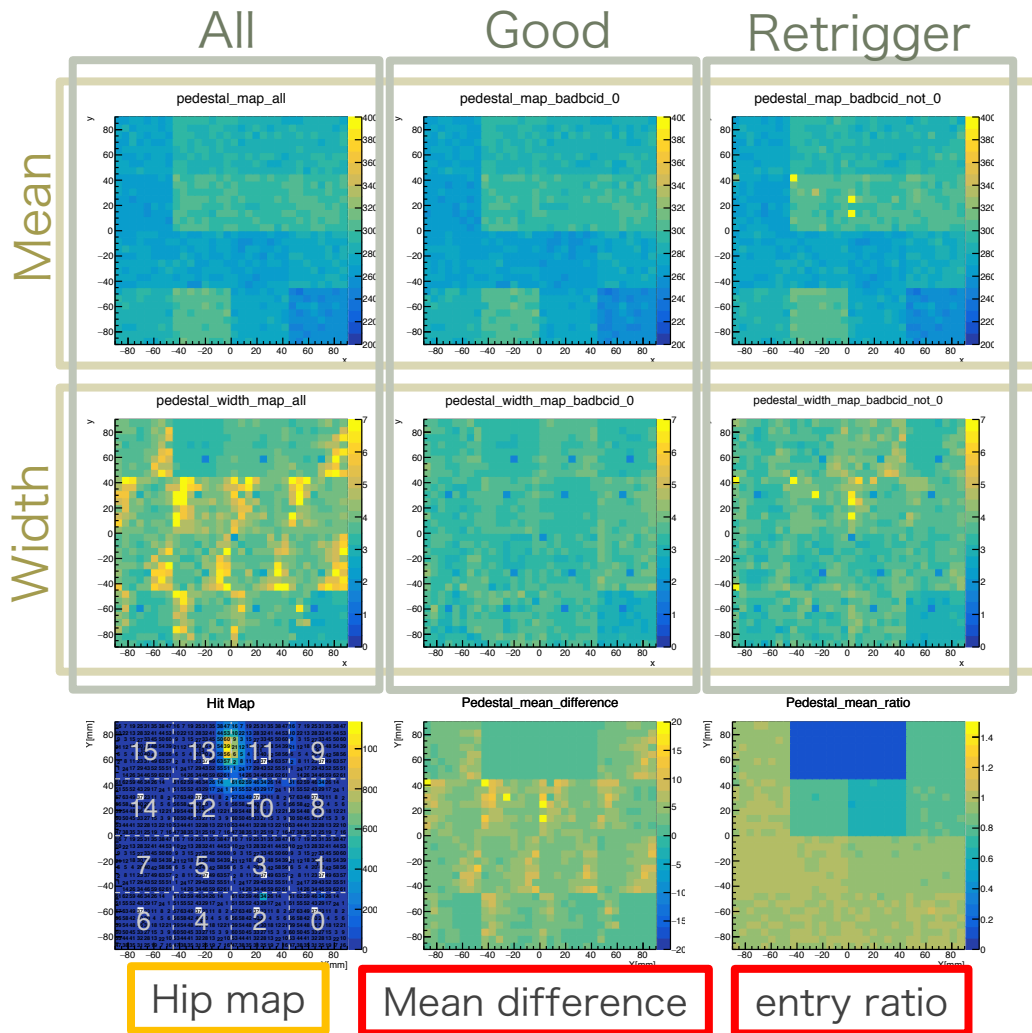
- from previous talk,
- TDC to real time calibration factors
 - 0.127 ns / TDC count (up)
 - 0.066 ns / TDC count (down)

timing resolution:
5.2 ± 1.6 ns

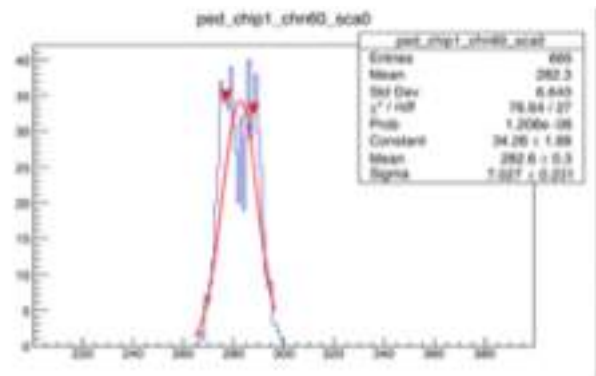
Remaining Issues

Double pedestal / Retrigger

- run 32015, slab P1



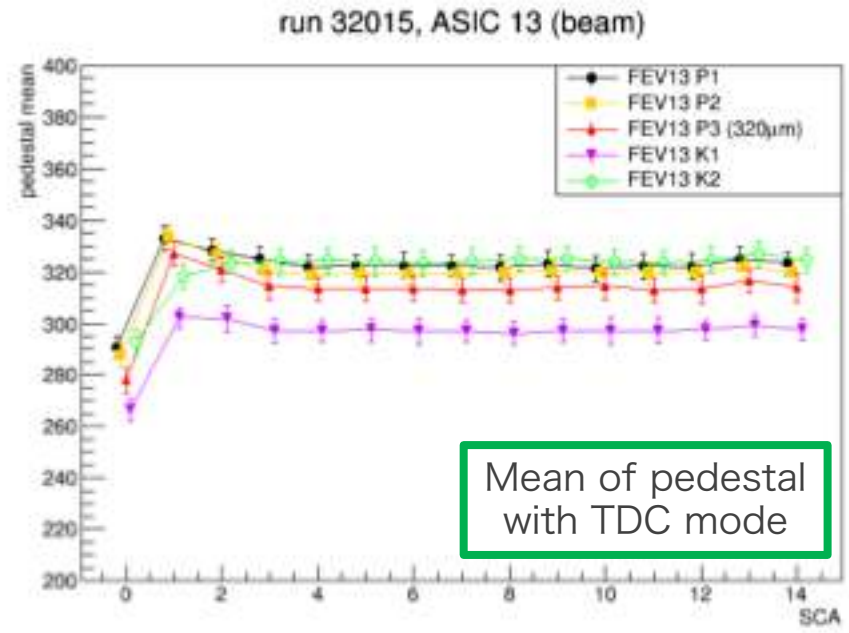
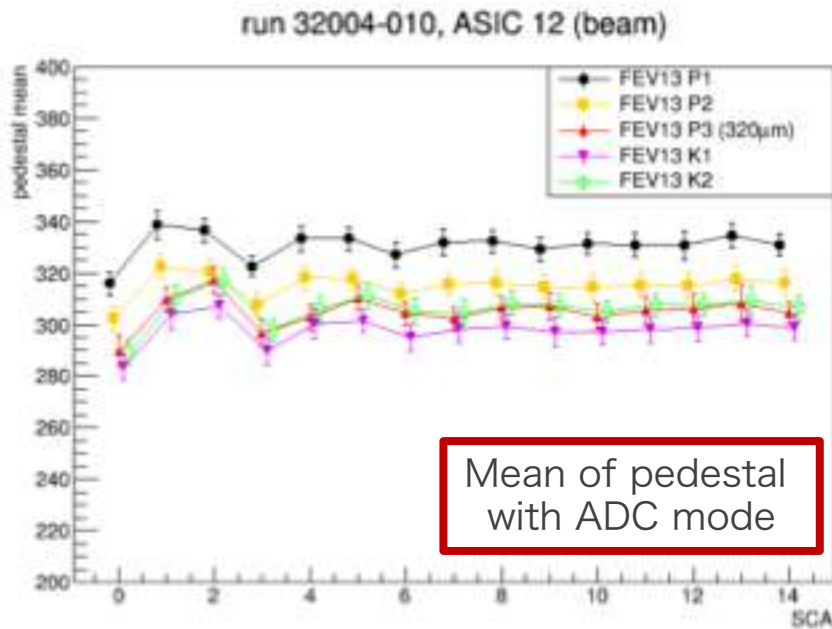
Retrigger event:
BCID is consecutive.



Double pedestal
by retrigger

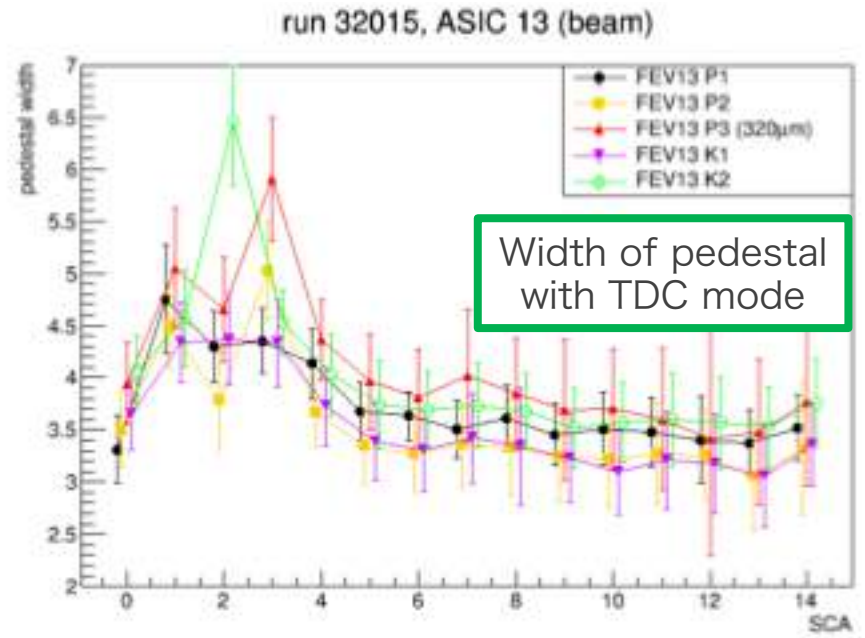
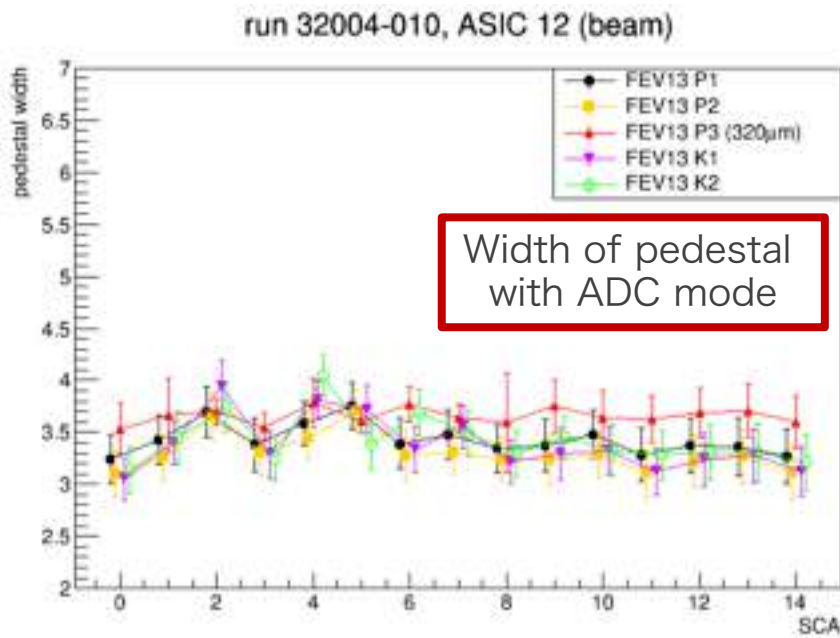
Pedestal difference between ADC/TDC mode

- We found the difference of pedestals between ADC/TDC mode.
- Memory-cell dependence is not same.
- In the first memory cell, the difference of typical Ped_mean is ~ 15 .



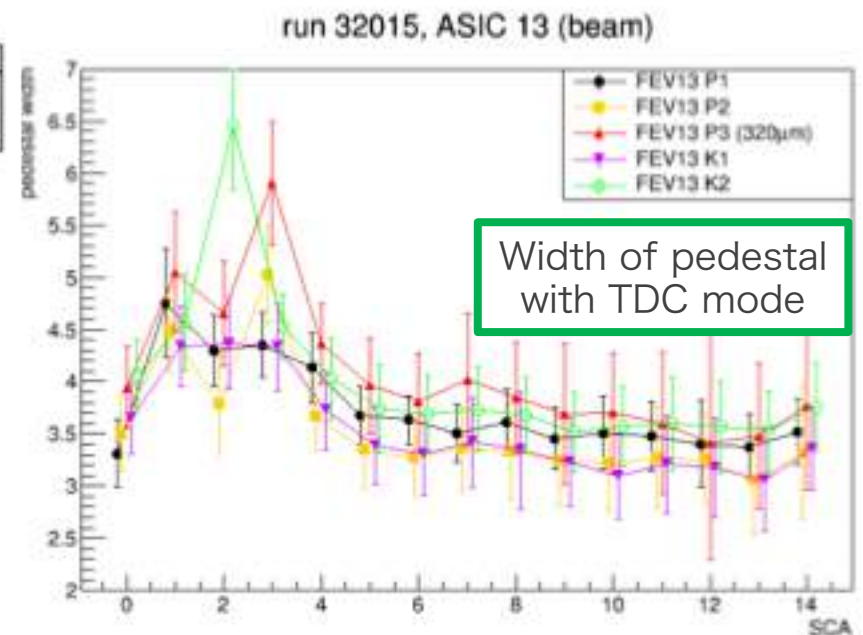
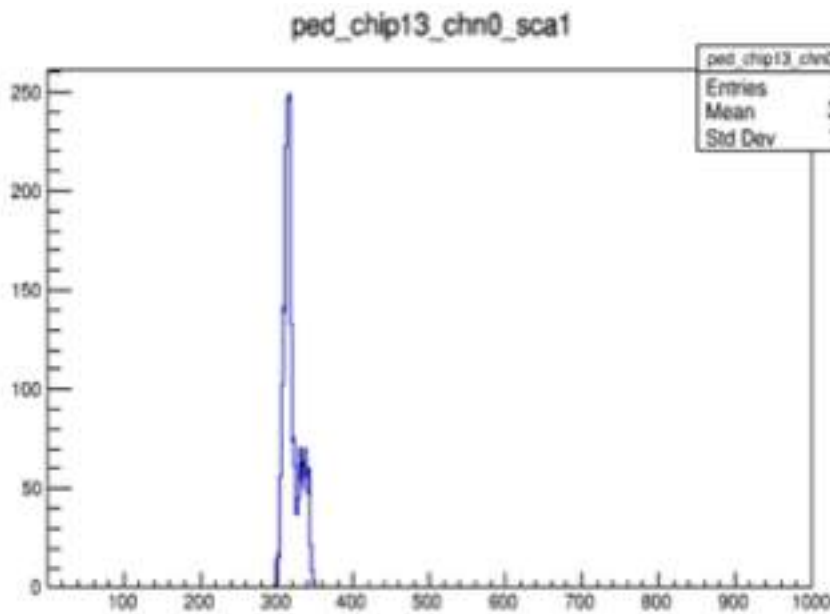
Pedestal difference between ADC/TDC mode

- We found the difference of pedestals between ADC/TDC mode.
- Memory-cell dependence is not same.
- In TDC mode, SCA~2 is worse.



Pedestal difference between ADC/TDC mode

- We found the difference of pedestals between ADC/TDC mode.
- Memory-cell dependence is not same.
- In TDC mode, SCA~2 is worse.



- There are double pedestal even after bcid selection in TDC mode.
- The criteria for identification of double pedestal is not optimized.

Work in progress.

Summary

- FEV13-Jp: 5 slabs from Kyushu U.
- BT 2019 DESY: **All the slabs worked consistently.**

- Pedestal study
 - Uniformity and Stability is verified.

- MIP calibration
 - MIP calibration is almost completed.
 - S/N is obtained for 5 slabs:

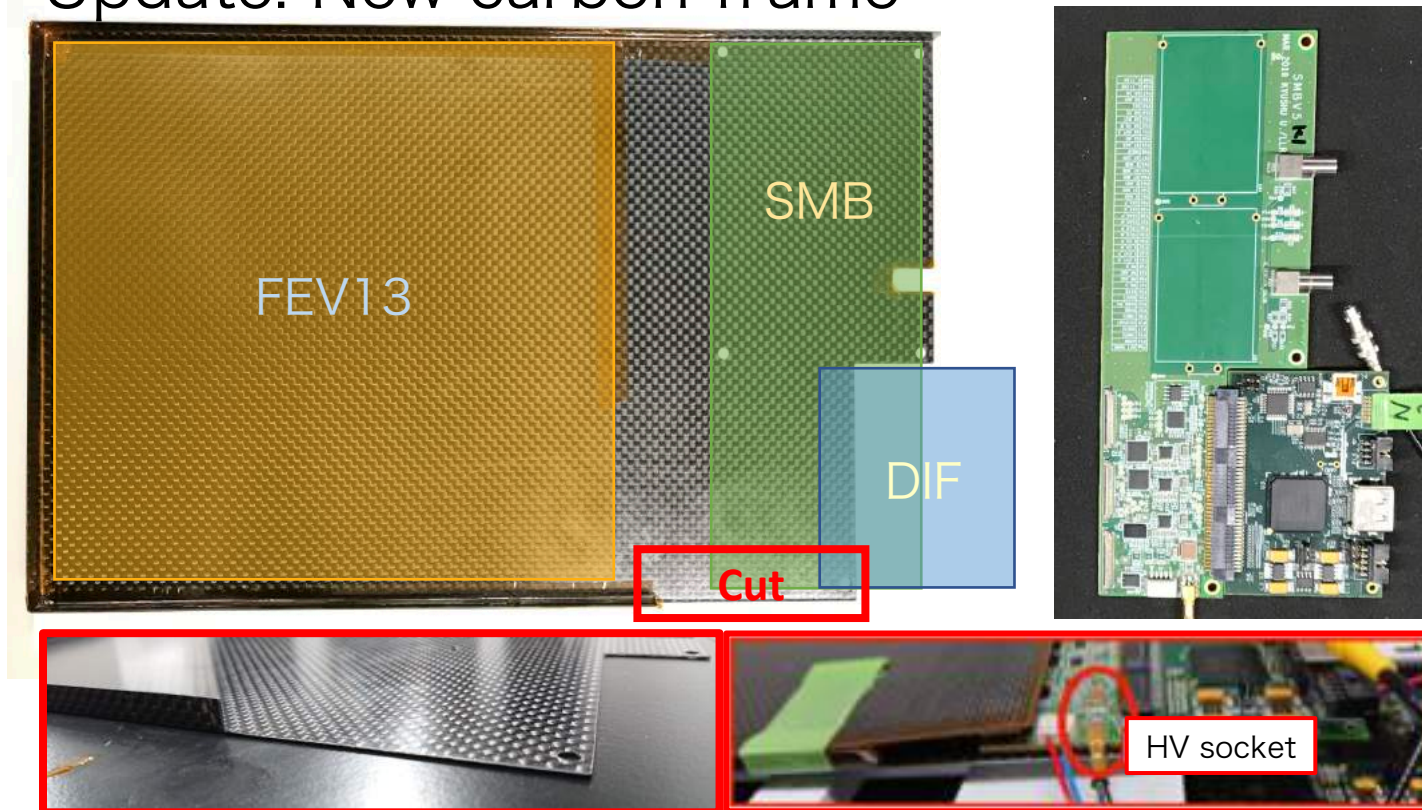
slab	P1	P2	P3	K1	K2
thickness	650 μ m	650 μ m	320 μ m	650 μ m	650 μ m
S/N _{ADC}	49.0	48.9	21.7	50.2	47.5

- Shower analysis
 - Event building has done and shower event is seen in event display.
 - We take a look at hit energy which is consistent with simulation result.
 - Work in progress.
- TDC test
 - Time walk is corrected, but very preliminary.
 - Timing resolution is obtained, however we need more detail study using injection.
- Several issues remain:
 - Retriggered events are removed practically although the cause is still unknown.
 - In TDC mode, pedestals become worse because of retriggers.

backup

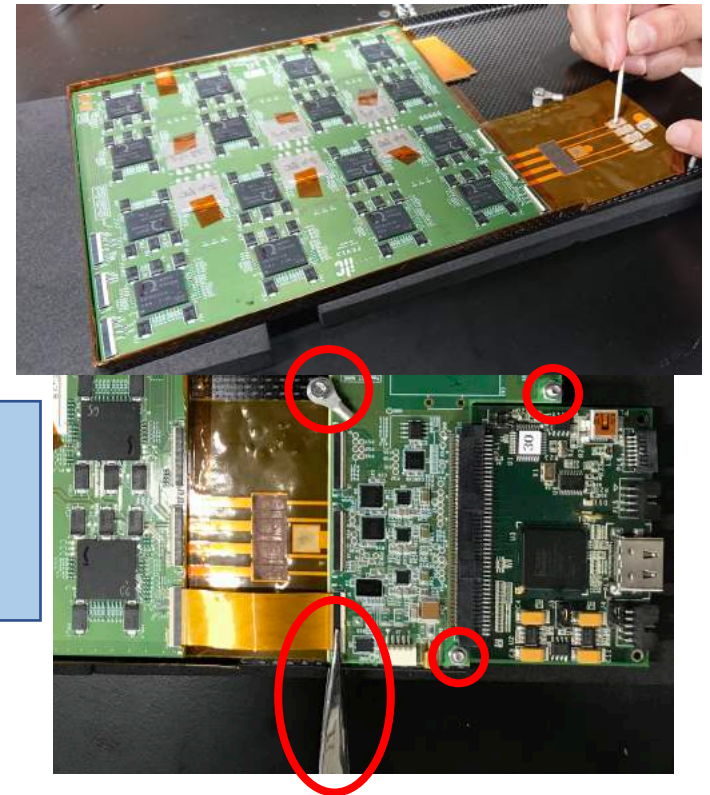
Hardware update

- Previous problems
 - Carbon frame was not optimized for FEV13.
 - HV connection between SMB and flex was fragile.
- Update: New carbon frame



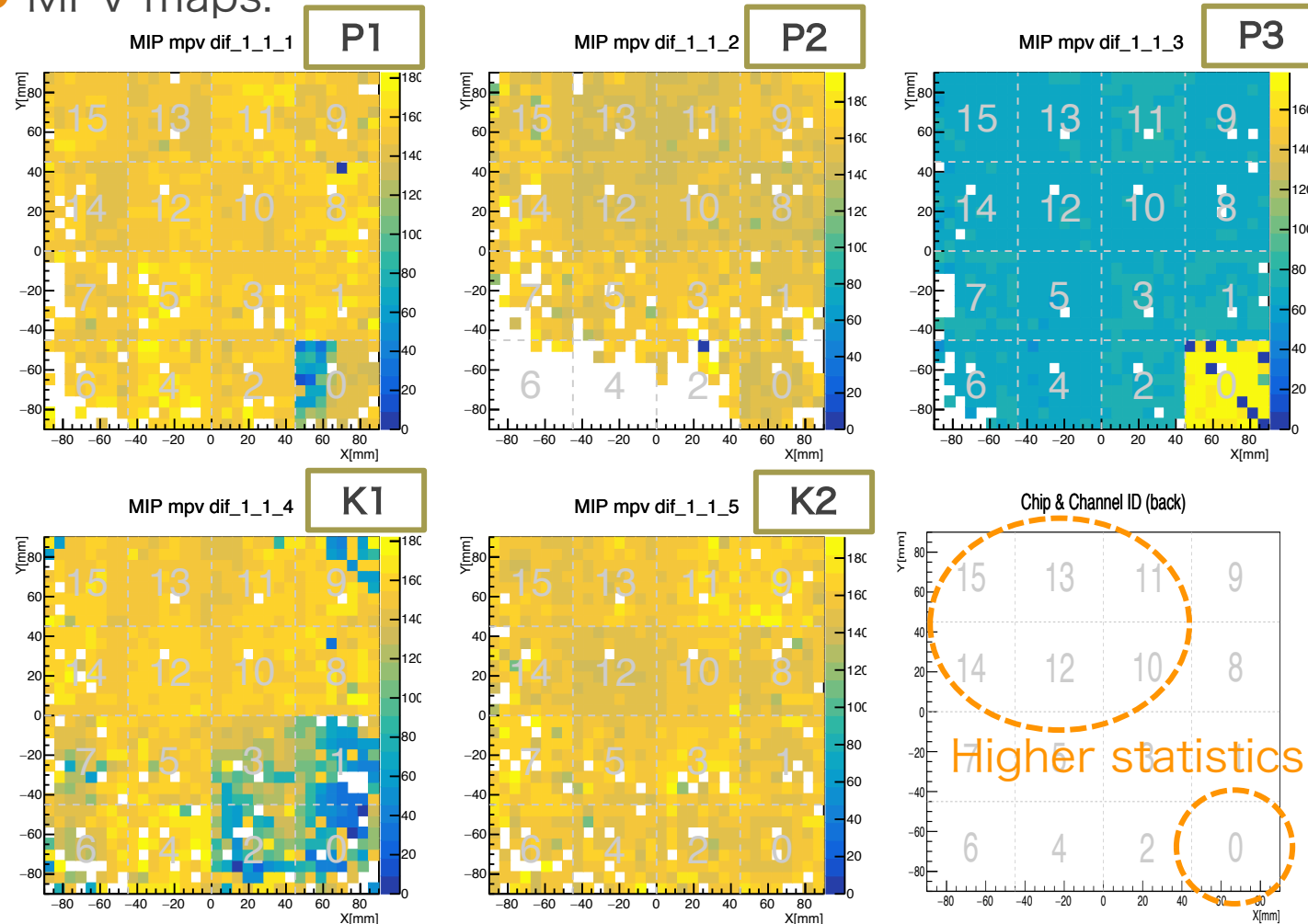
Hardware update

- Previous problems
 - Carbon frame was not optimized for FEV13.
 - HV connection between SMB and flex was fragile.
- Update: Conductive adhesive



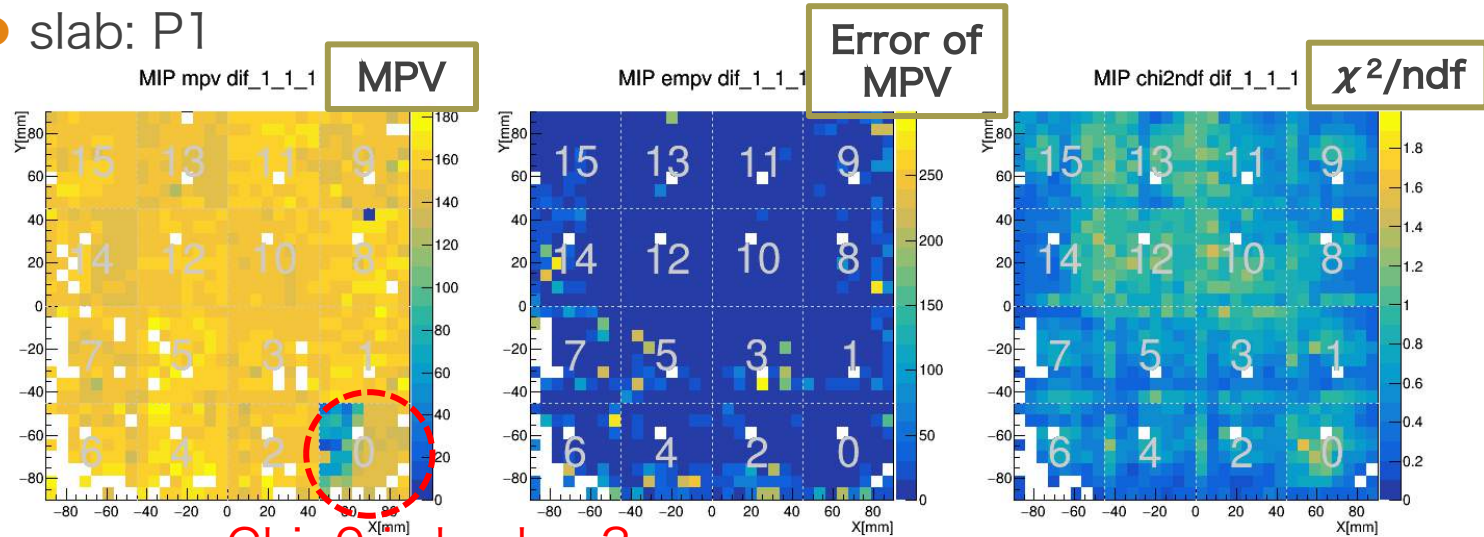
MIP calibration

- MPV maps:

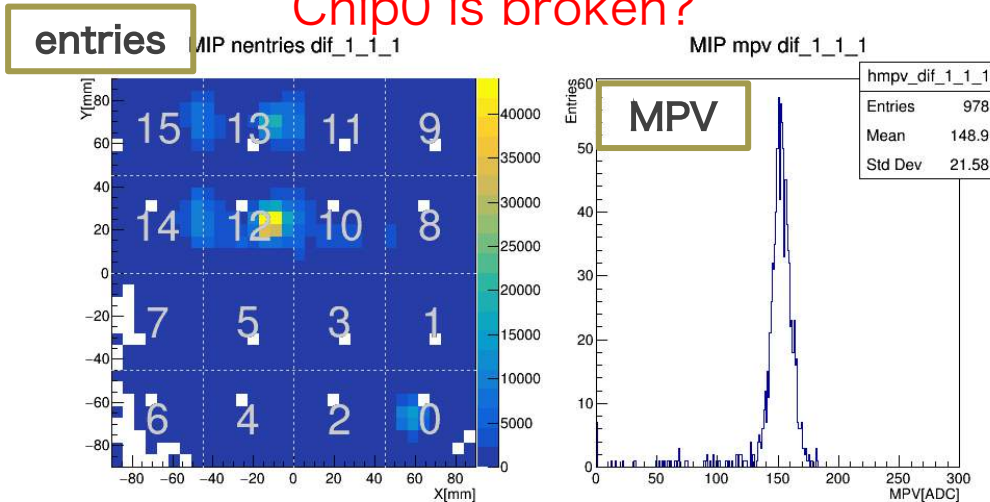


MIP calibration

- slab: P1



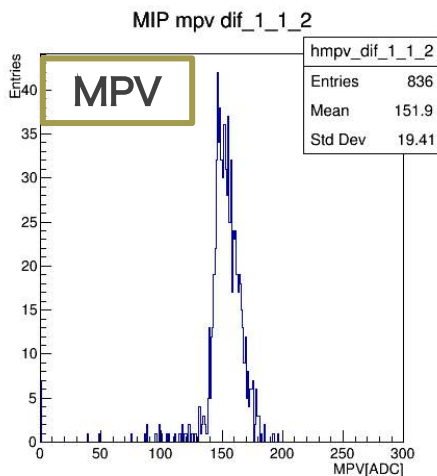
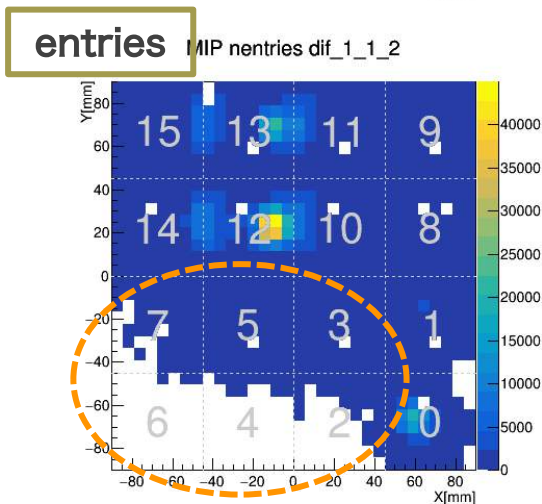
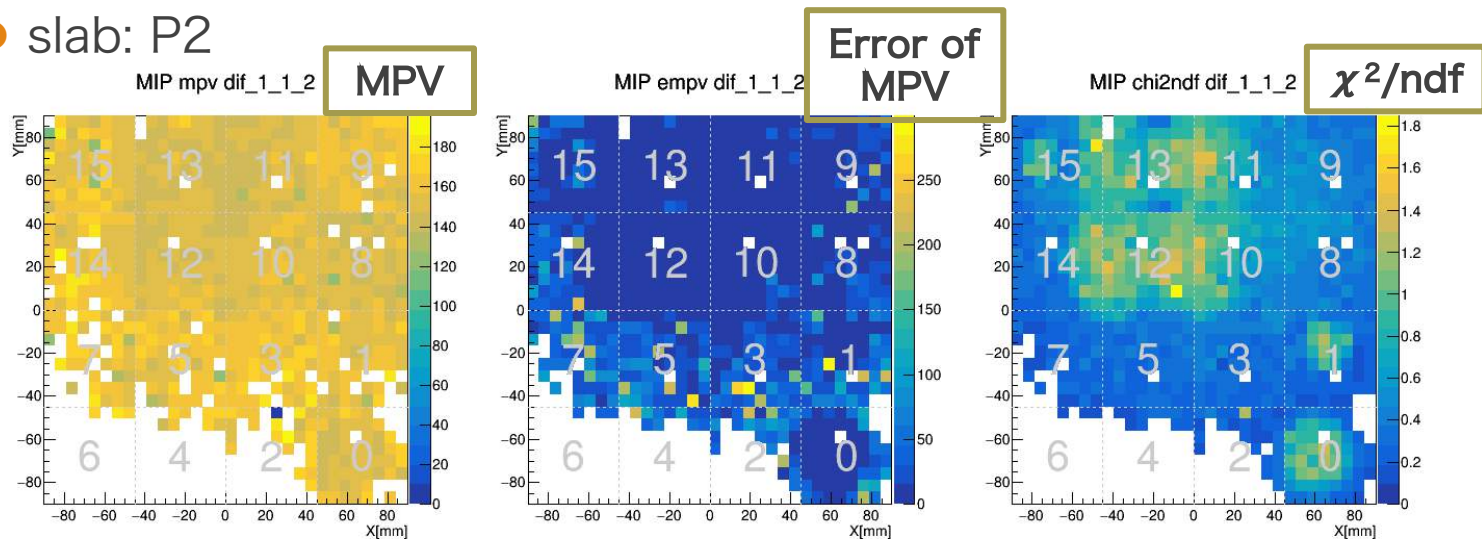
Chip0 is broken?



Preliminary

MIP calibration

- slab: P2

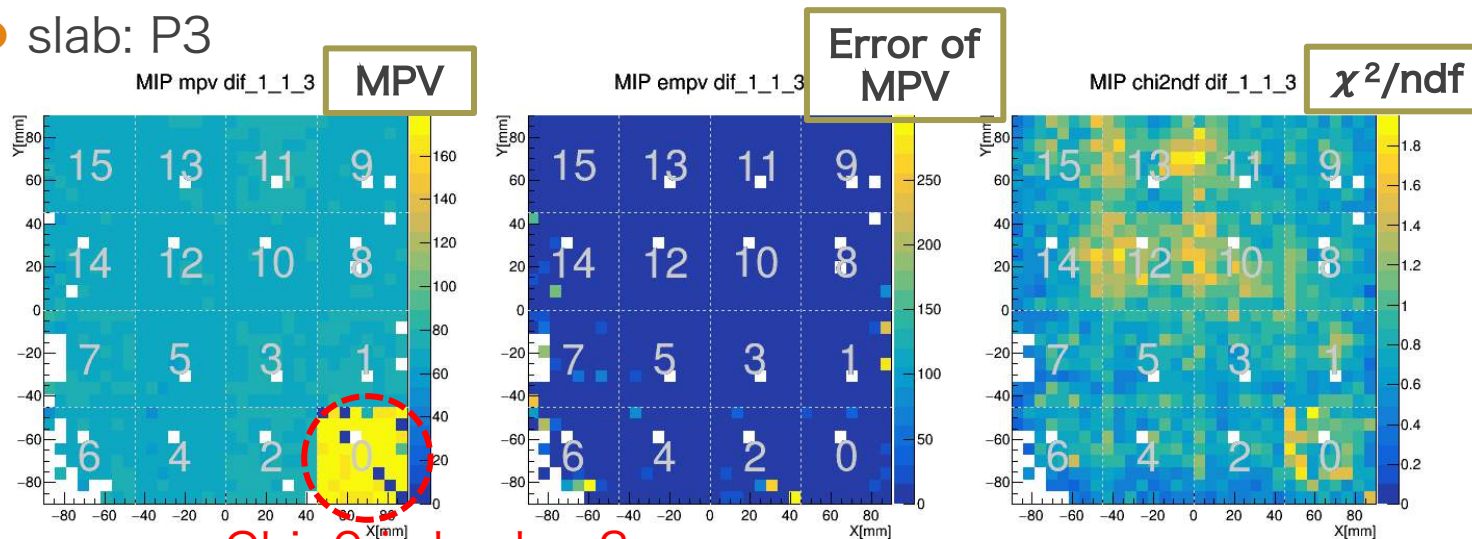


Preliminary

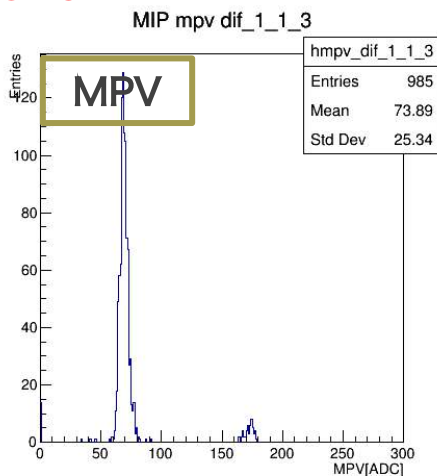
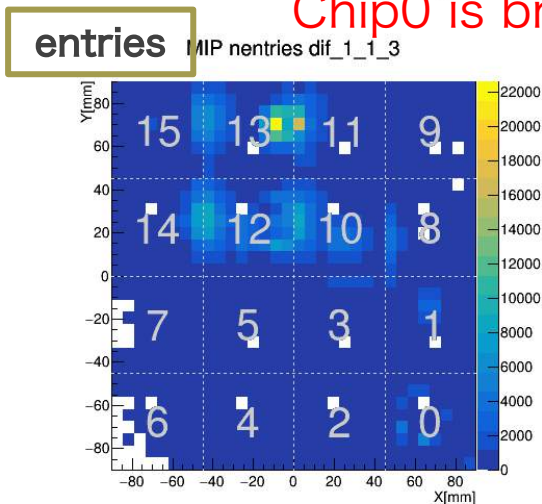
Low-statistics because
DIF was broken in position scan

MIP calibration

- slab: P3



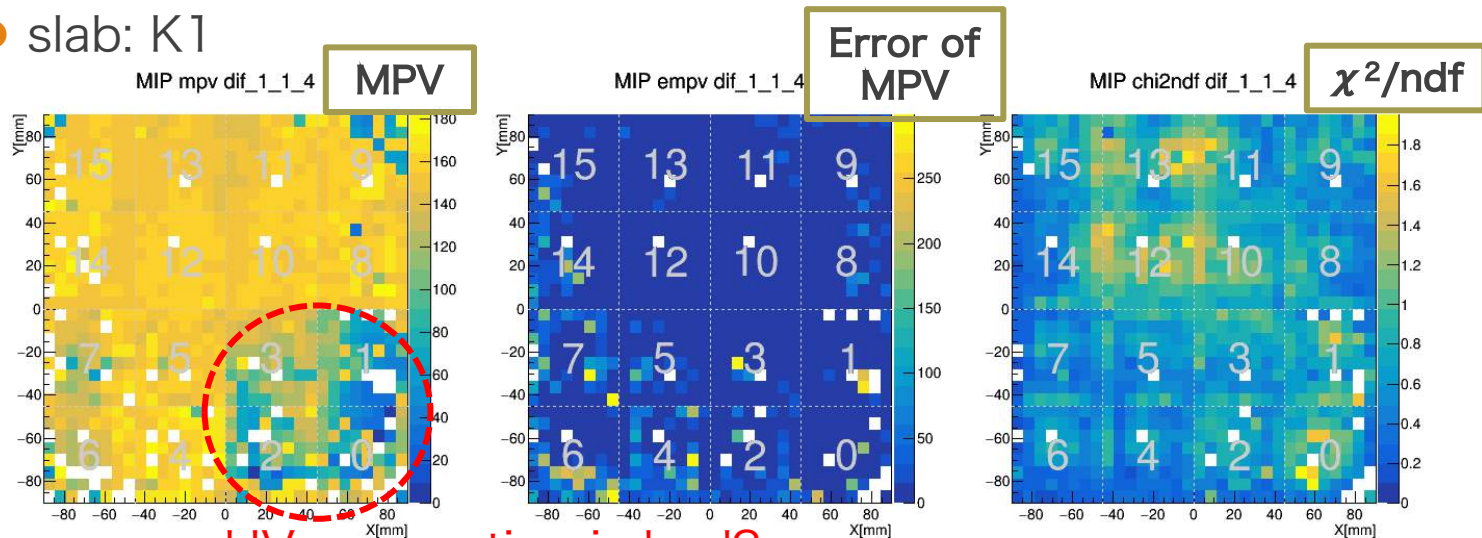
Chip0 is broken?



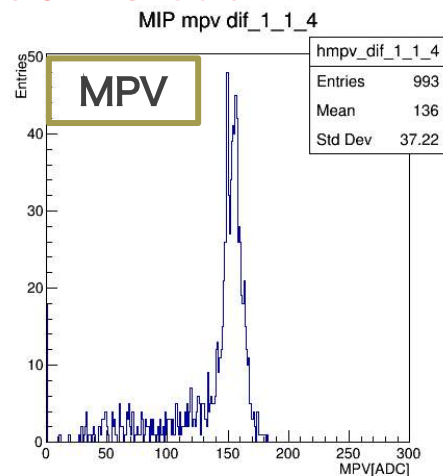
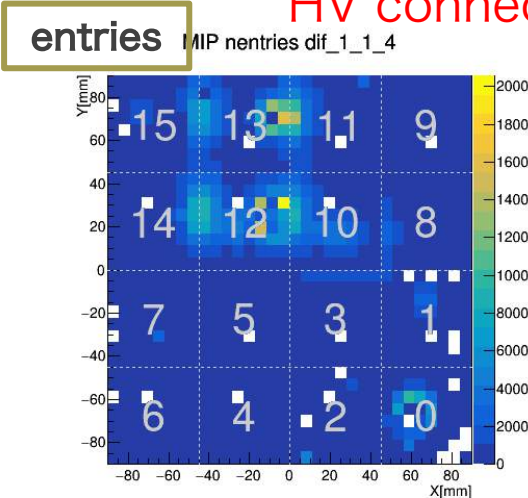
Preliminary

MIP calibration

- slab: K1



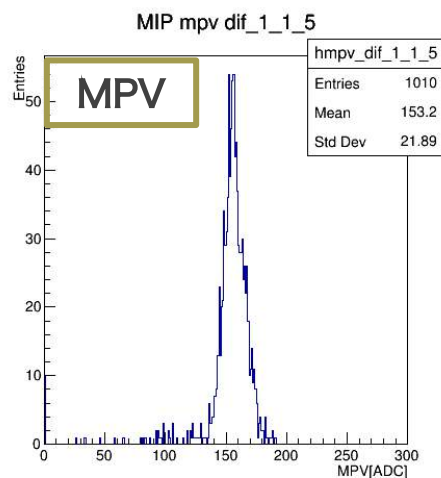
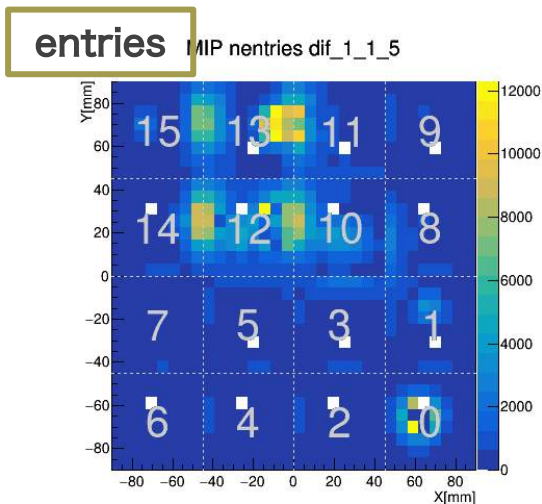
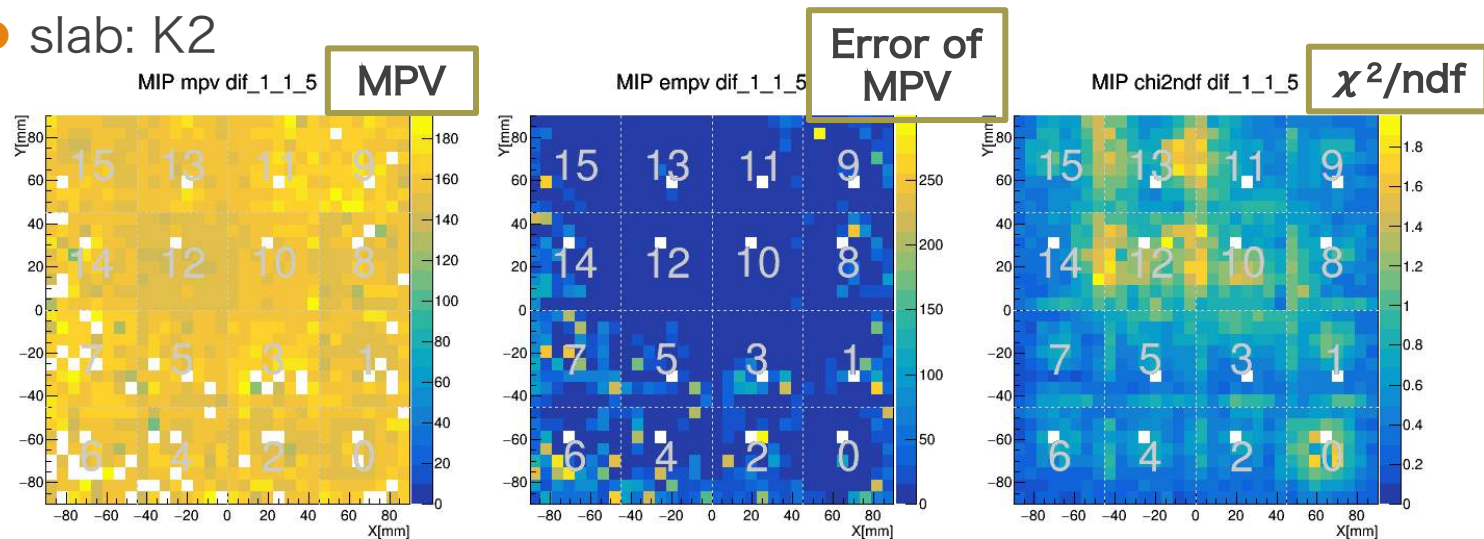
HV connection is bad?



Preliminary

MIP calibration

- slab: K2



Good!

Preliminary

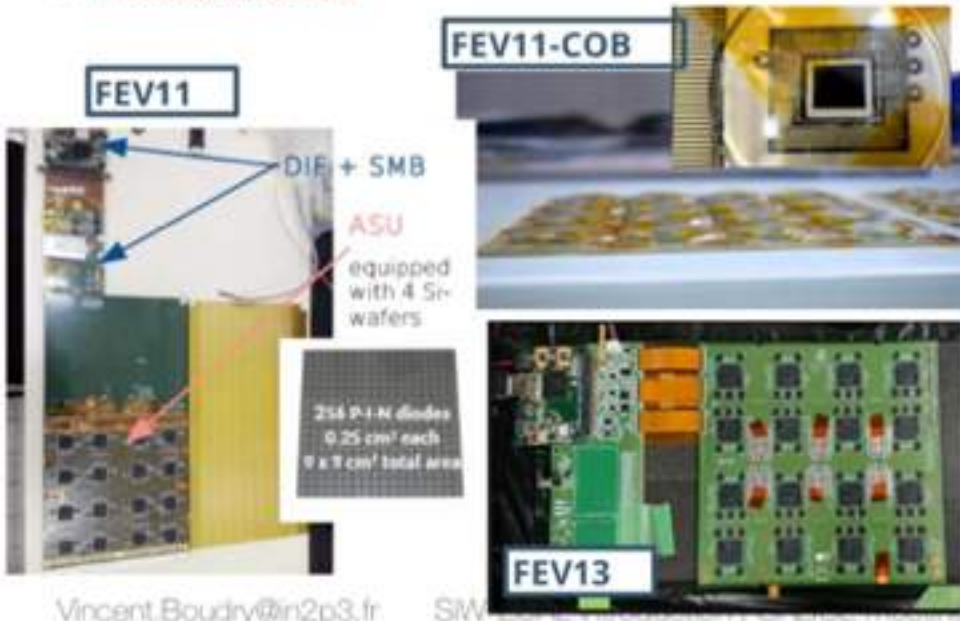
R&D of SiW-ECAL technological prototypes



ASU: 12 years of R&D

Most complex element: electro-mechanical integration

- Distrib / Collect signals from VFE (ASICs), Analog & Digital with dyn. range ≥ 7500
- Mechanical placer & holder for Wafers \rightarrow precision
- Thickness constraints



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SiW

Milestone	Date	Object	Details	REM
1 st ASIC proto	2007	SK1 on FEV4	36 ch, 5 SCA	proto, lim @ 2000 mips
1 st ASIC	2009	SK2	64ch, 15 SCA	3000 mips
1 st prototype of a PCB	2010	FEV7	8 SK2	COB
1 st working PCB	2011	FEV8	16 SK2 (1024 ch)	CIP (QGFP)
1 st working ASU in BT	2012	FEV8	4 SK2 readout (256ch)	best S/N - 14 (HG), no PP retriggers 50-75%
1 st run in PP	2013	FEV8-CIP		BGA, PP
1 st full ASU	2015	FEV10	4 units on test board 1024 channel	S/N - 17-18 (High Gain) retrigger - 50%
1 st SLABs	2016	FEV11	7 units	
pre-calo	2017	FEV 11	7 units	S/N - 20 (12) _{TH} 6-8 % masked
1 st technological ECAL	2018	SLABvFEV11 & FEV13 SK2a+ Compact stack	SK2 & SK2a (>timing)	Improved S/N Timing...

R&D of SiW-ECAL technological prototypes

Beam-test 2015-2018

